

Gallium Nitride HEMTs: advantages, opportunities and challenges

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Outline

- Introduction & GaN properties
- Applications opportunities
- Open issues
 - Materials
 - Technology (E-Mode, Breakdown, Vertical vs lateral,)
 - Parasitic & Reliability
- GaN Activities within IU.NET
- Conclusions



Introduction to the GaN-HEMTs

Back to the material properties:

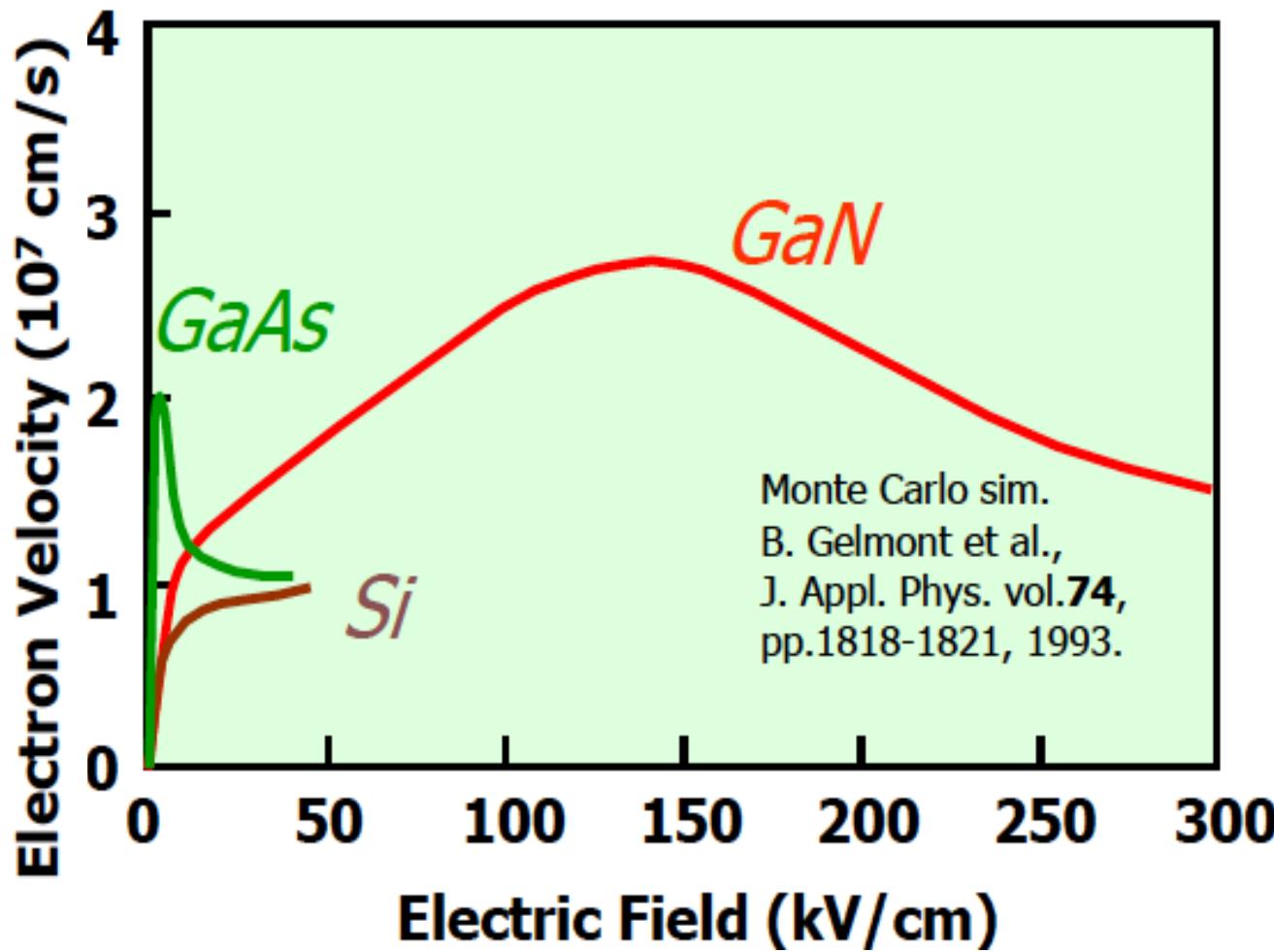
	GaN	InN	AlN	Si
Bandgap (eV)	3.4 eV	0.6 eV	6.4 eV	1.1 eV
Mobility ($\text{cm}^2\text{V}^{-1}\text{s}^{-1}$)	1500	3000	300	1000
Breakdown Field (MV/cm)	3	Low	11	0.3
Effective Mass	$0.21 m_e$	$0.09 m_e$	$0.4 m_e$	$0.19 m_e$
Velocity (cm/s)	2×10^7	2×10^8	-	1.0×10^7
Polarization	High charge, carrier confinement			

[1] U. K. Mishra, P. Parikh, Y.F. Wu, "AlGaN/GaN HEMTs—An Overview of Device Operation and Applications" IEEE Proc. Vol. 90, No. 6, p. 1022, June 2002.

[2] U. K. Mishra, L. Shen, T. E. Kazior, Y. F. Wu, "GaN-Based RF Power Devices and Amplifiers" IEEE Proceedings, Vol. 96, No. 2, p. 287, February 2008.



Introduction to the GaN-HEMTs



Introduction & Motivations

ADVANTAGEOUS IN
POWER-SUPPLY CIRCUITS

HIGH OPERATING TEMPERATURE
DUE TO LARGE BANDGAP AND
HIGH POTENTIAL BARRIER

ADVANTAGEOUS IN
POWER-SUPPLY CIRCUITS

HIGH BREAKDOWN STRENGTH
DUE TO LARGE BANDGAP

ADVANTAGEOUS IN
RF CIRCUITS

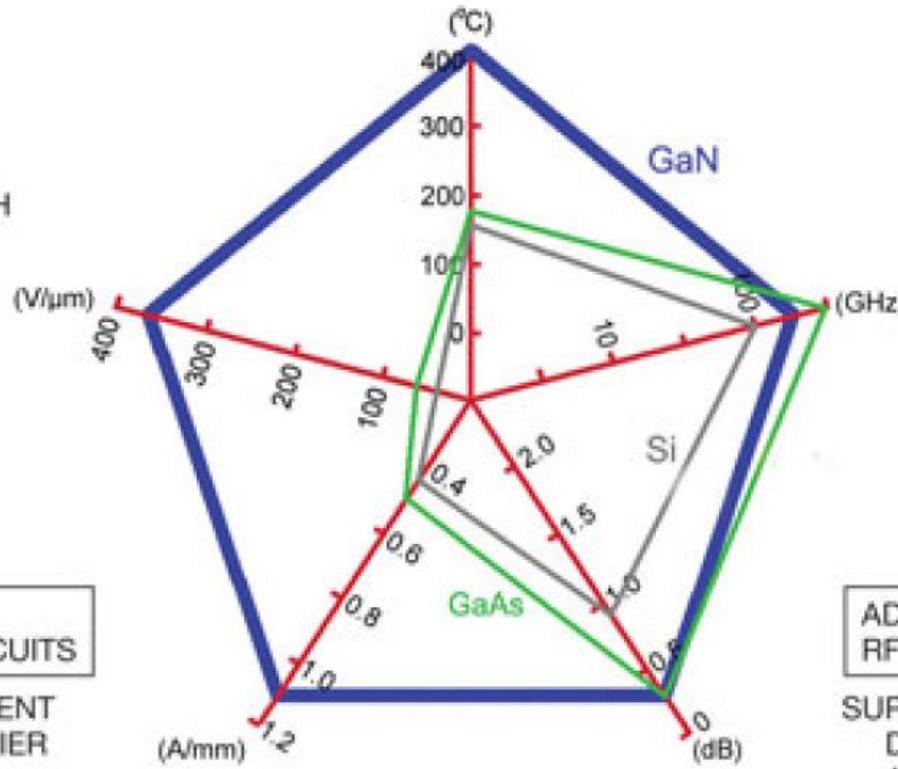
HIGH MAXIMUM
OSCILLATION FREQUENCY
DUE TO HIGH ELECTRIC
FIELD SATURATION SPEED
AND LOW PARASITIC
CAPACITY

ADVANTAGEOUS IN
POWER-SUPPLY CIRCUITS

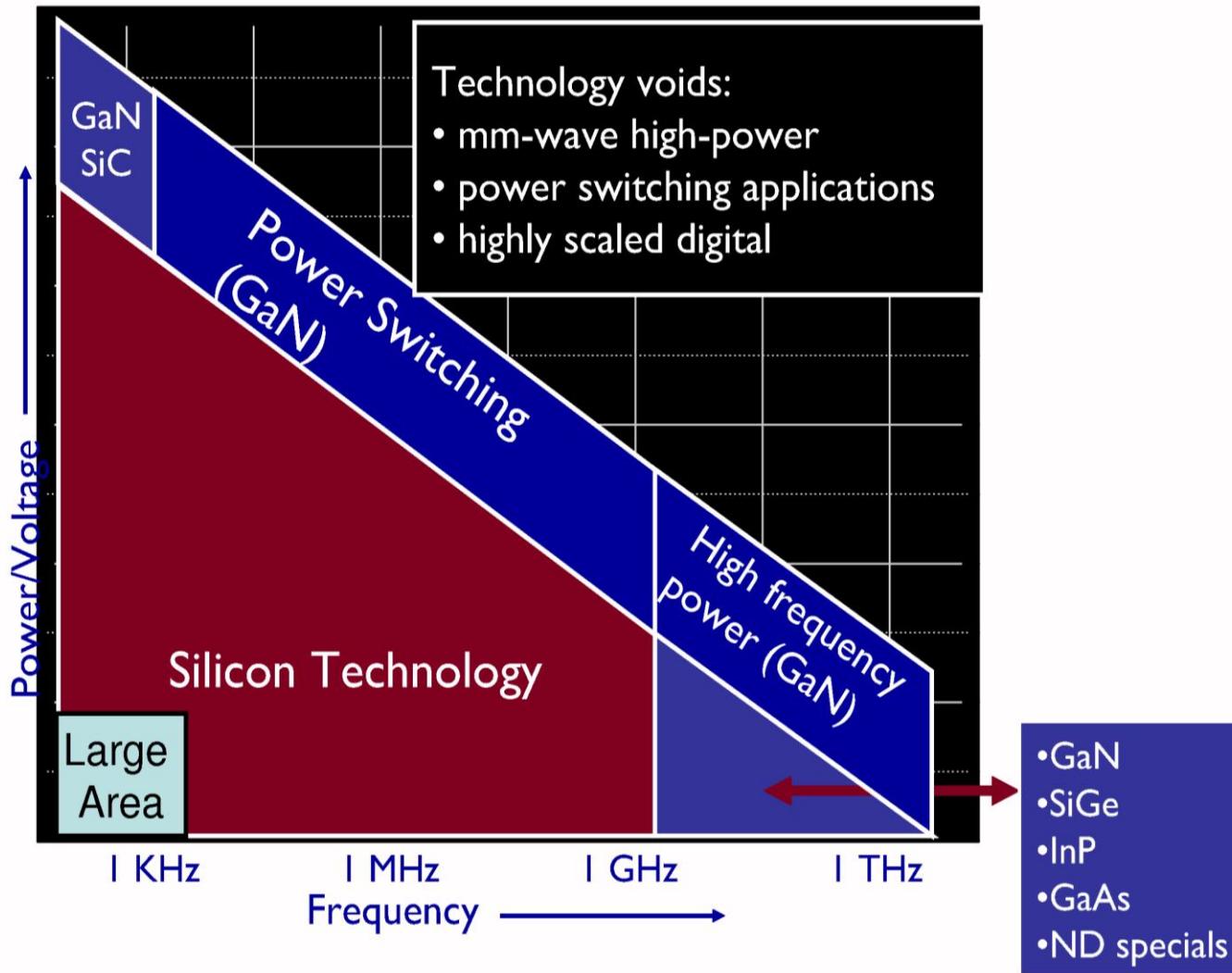
HIGH MAXIMUM CURRENT
DUE TO HIGH CARRIER
DENSITY AND HIGH
ELECTRON MOBILITY

ADVANTAGEOUS IN
RF CIRCUITS

SUPERIOR NOISE FACTOR
DUE TO LOW CARRIER SCATTERING
AND LOW RF LOSSES



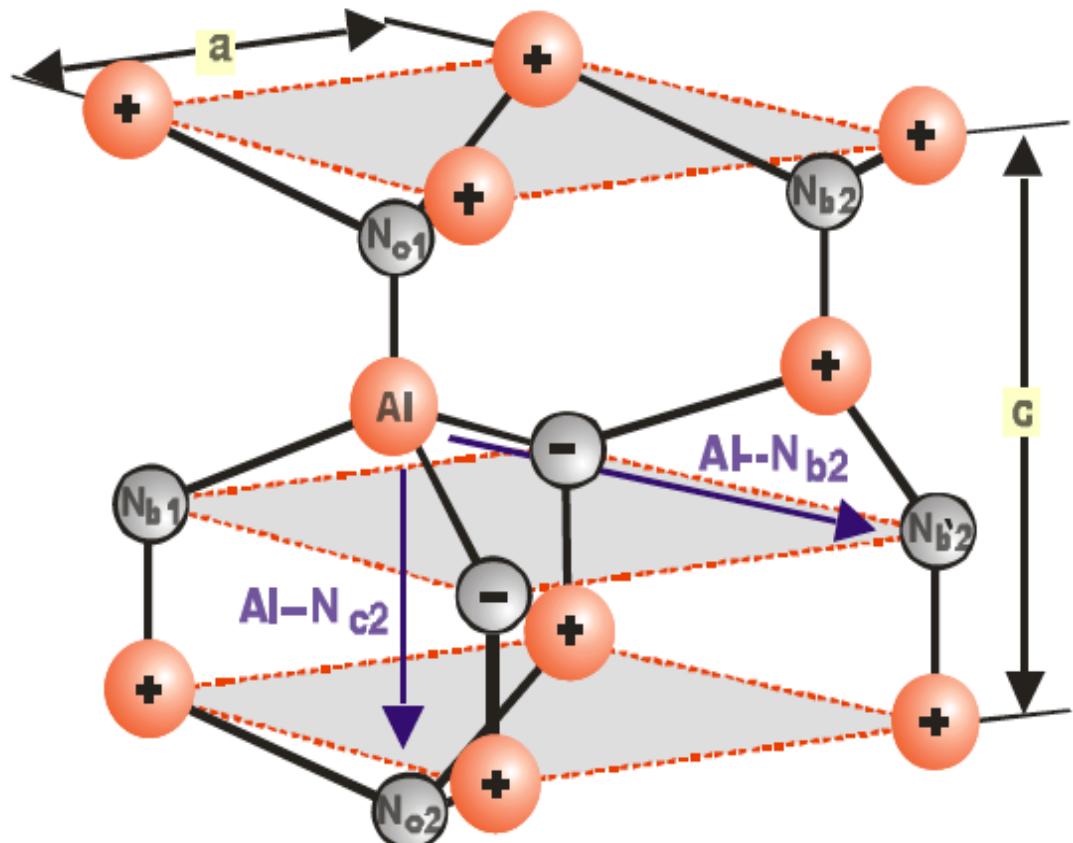
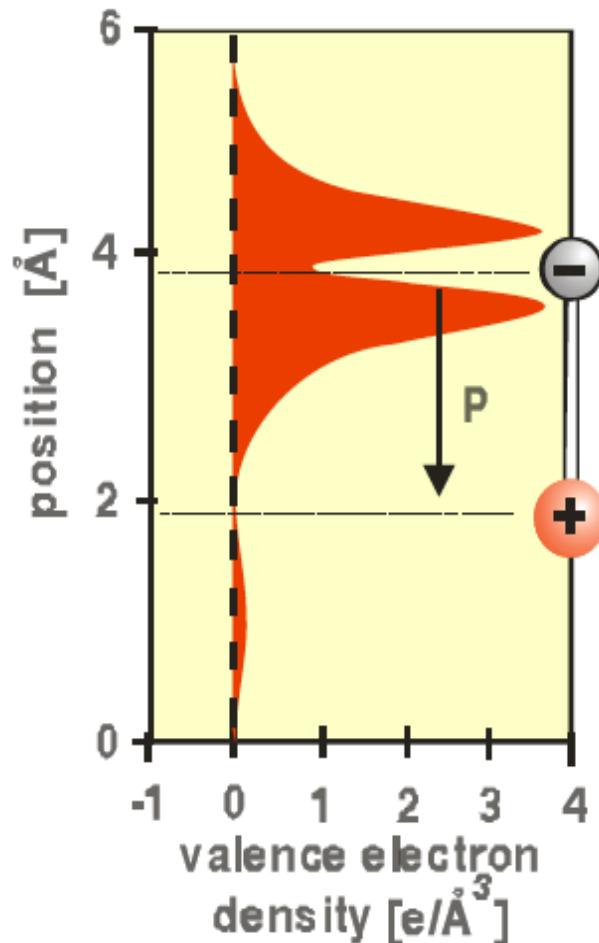
Introduction to the GaN-HEMTs



courtesy: Umesh Mishra, UCSB



GaN: Polar material

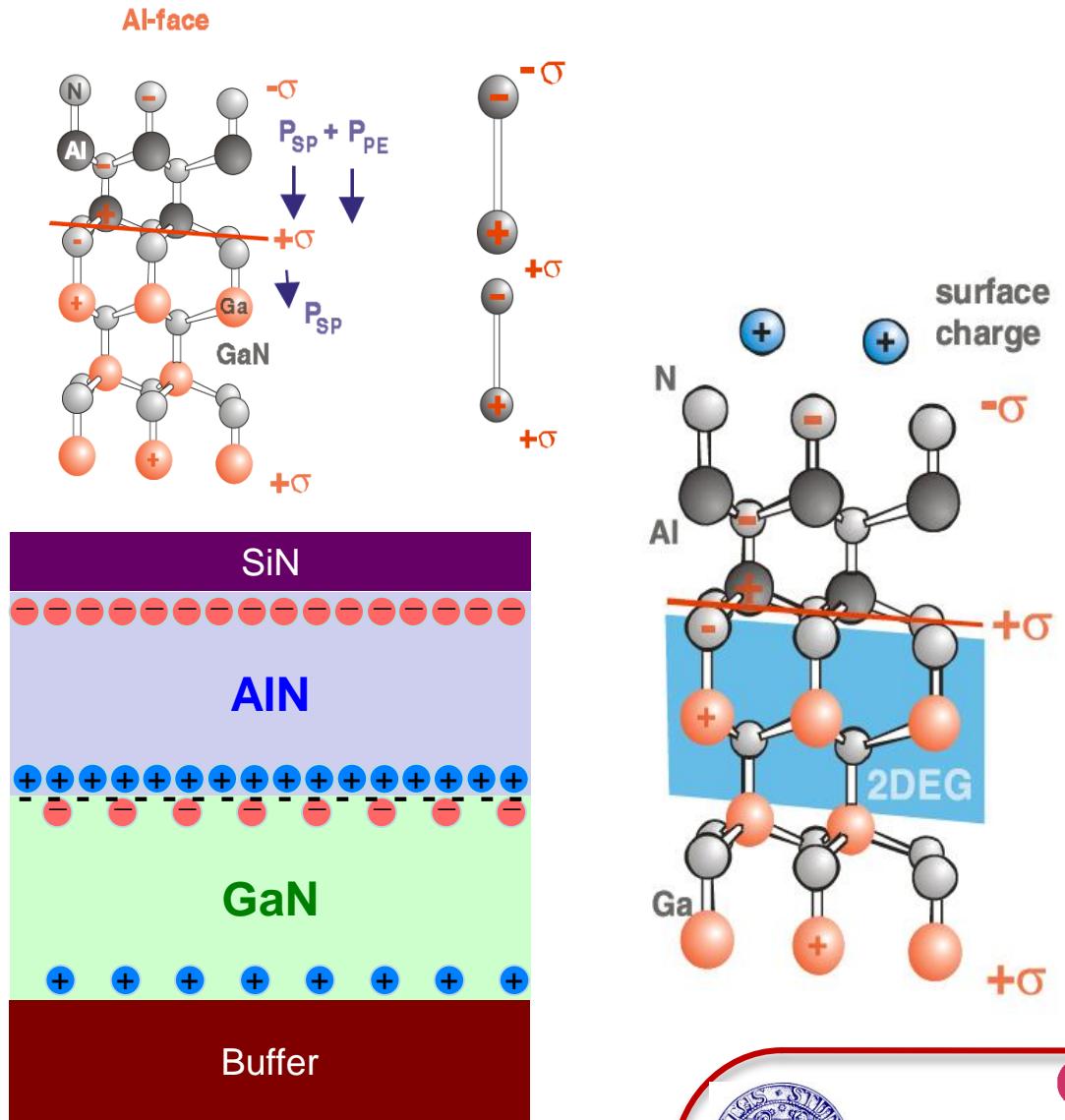
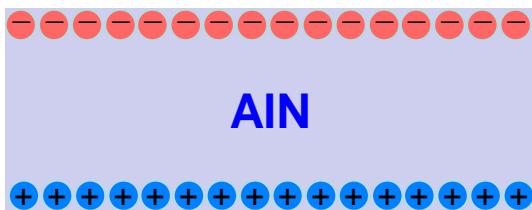
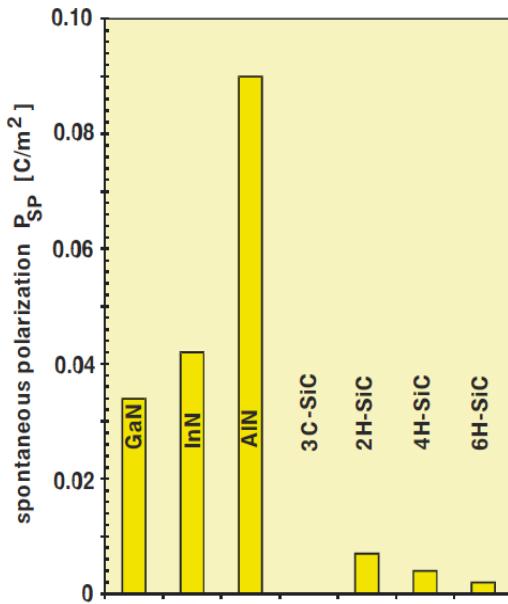


O. Ambacher et al JAP 87, 334 (2000)

O. Ambacher et al. J.Appl. Phys. 85, 3222 (1999)



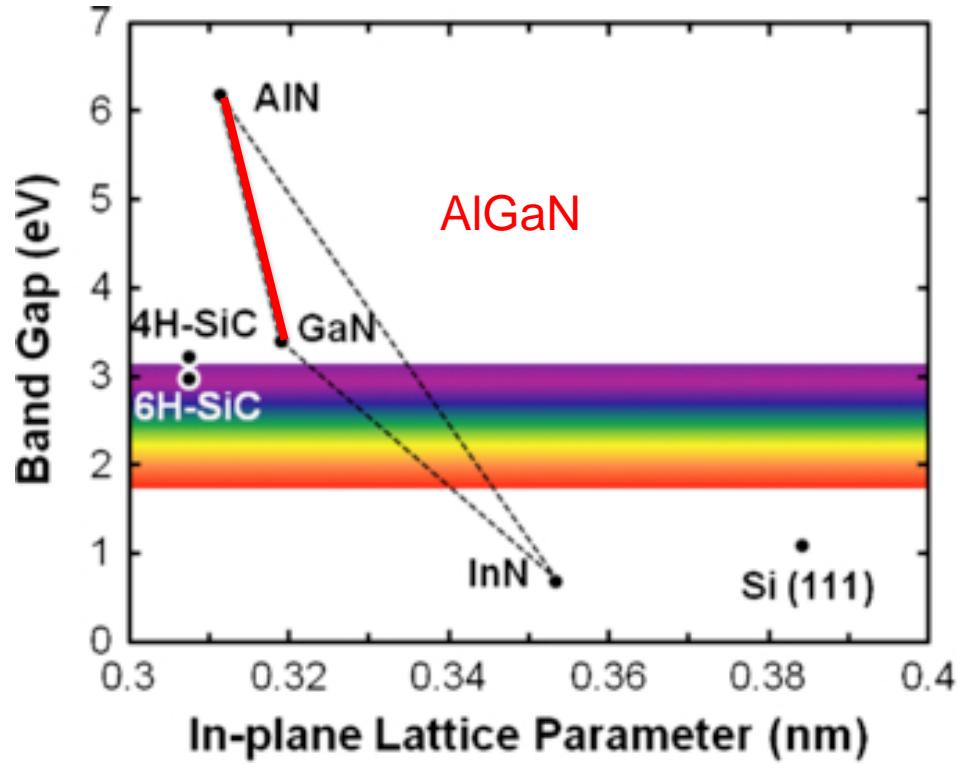
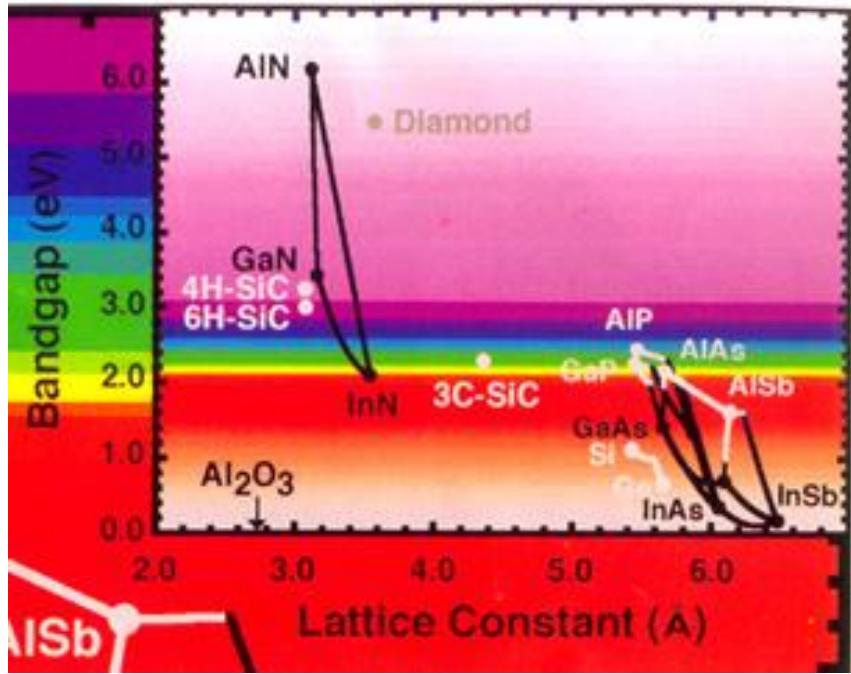
GaN: Polar material



GaN: Polar material

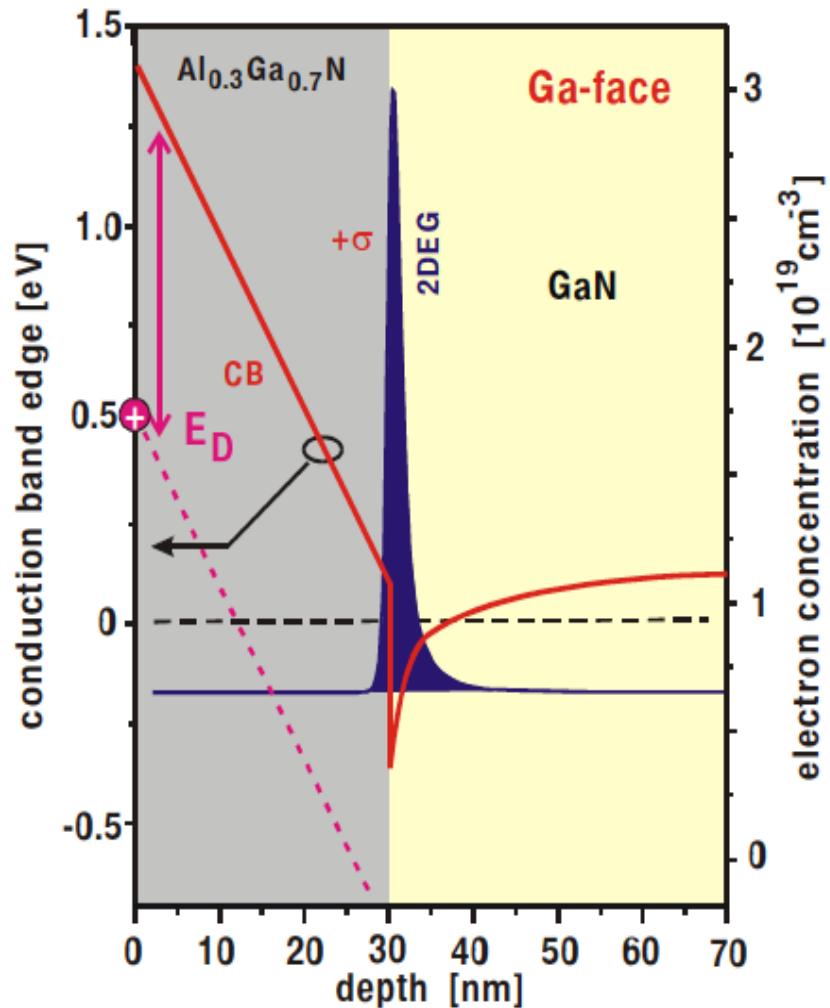
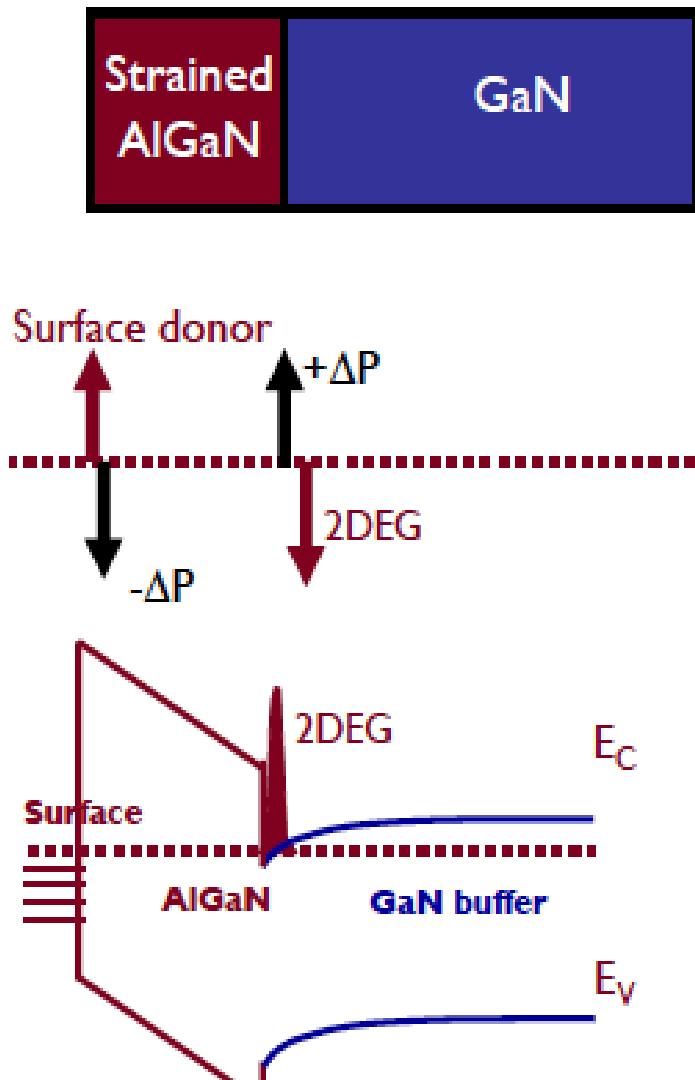
GaN/AlGaN

OK the lattice constant



Typically 20-25%
Al composition

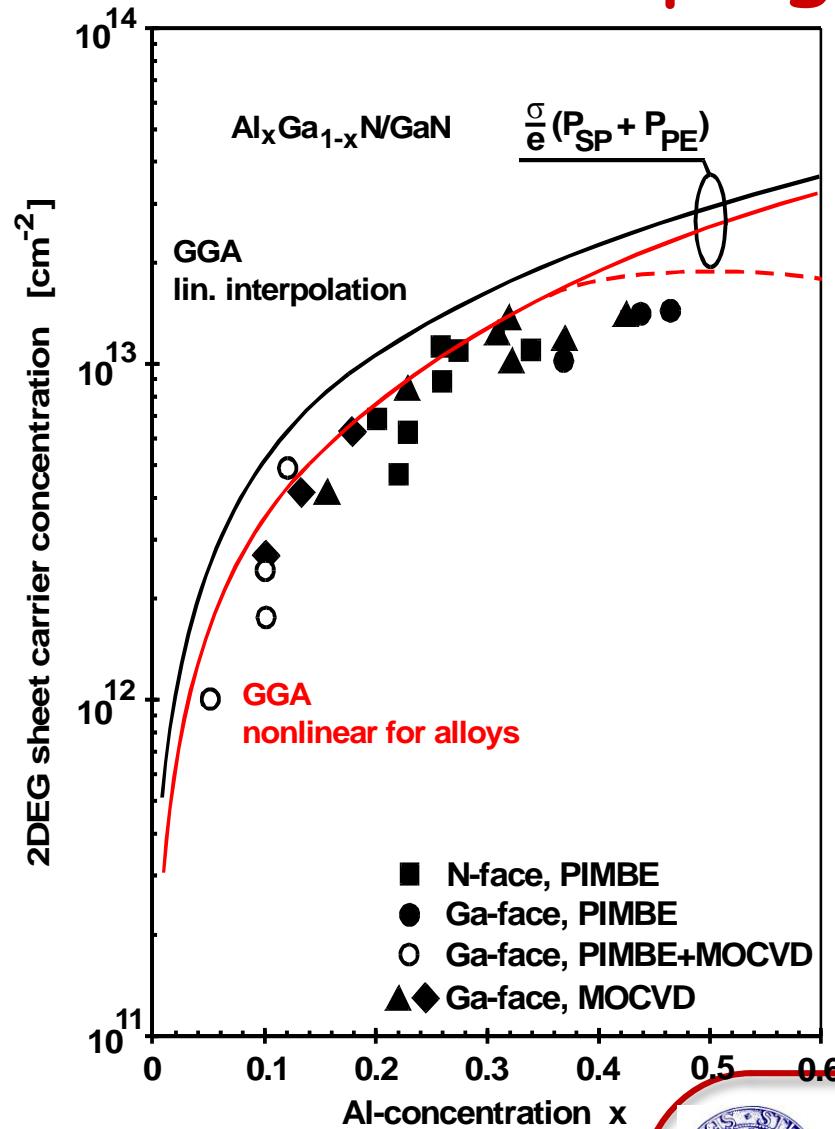
GaN HEMTs: 2DEG w/o doping!



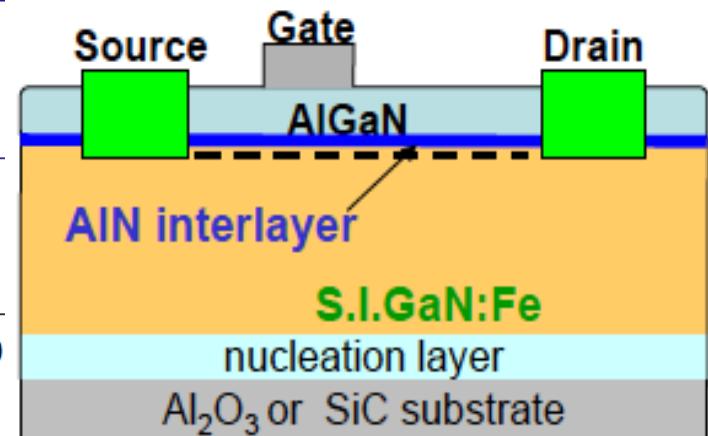
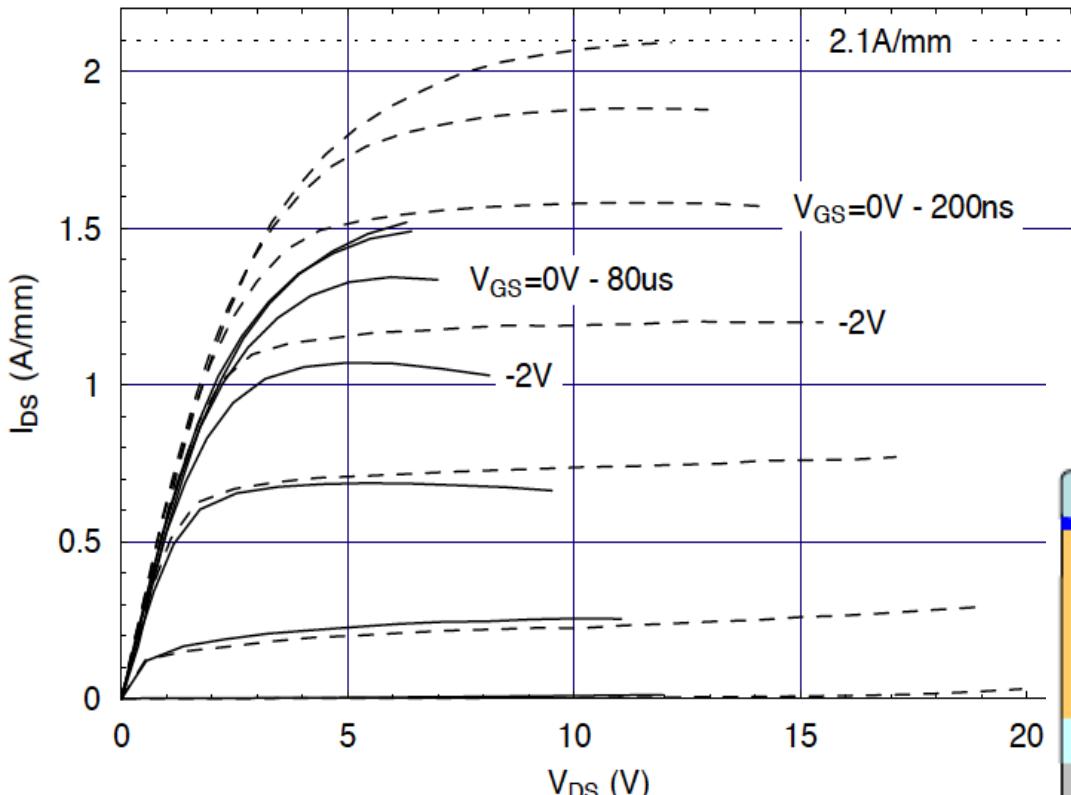
GaN HEMTs: 2DEG w/o doping!

O. Ambacher et al JAP
87, 334 (2000)
O. Ambacher et al.
J.Appl. Phys. 85, 3222
(1999)

generalized gradient
approximation (GGA)
plasma-induced molecular
beam epitaxy (PIMBE)



Basic HEMTs design $I_{Dmax} = 2.1 A/mm$



A. Chini, R. Coffie, G. Meneghesso, E. Zanoni, D. Buttari, S. Heikman, S. Keller, and U. K. Mishra

“A 2.1A/mm Current Density AlGaN/GaN HEMT”

IEE Electronics Letters, vol. 39, N. 7, April 2003, pp. 625-626



Figure of Merit in semiconductors

Table 1 Figures of merit of various semiconductors

	Si	GaAs	4H-SiC	GaN
JFM	1	11	410	790
KFM	1	0.45	5.1	1.8
BFM	1	28	290	910
BHFM	1	16	34	100

JFM : Johnson's figure of merit for high frequency devices = $(E_b V_s / 2\pi)^2$

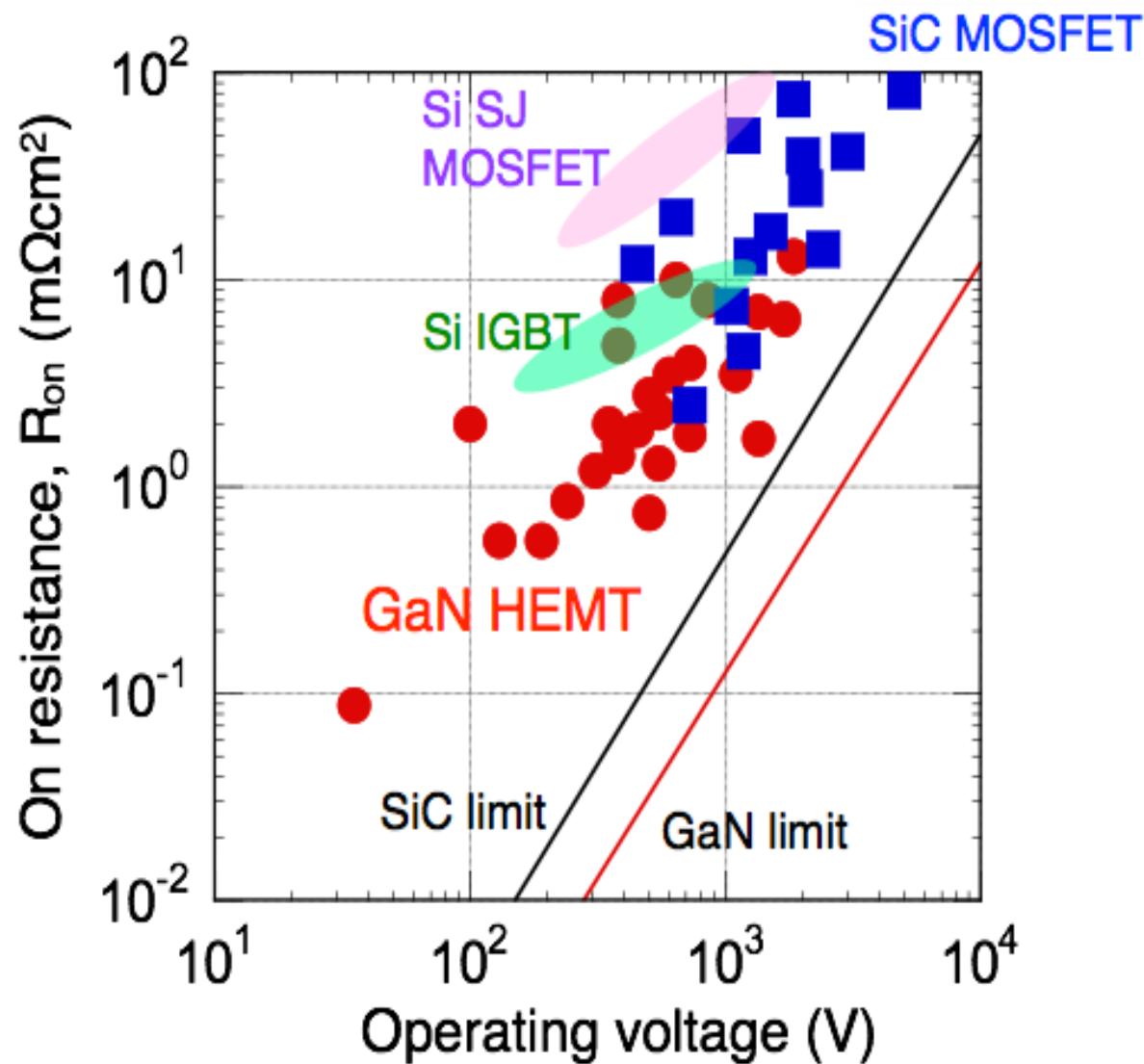
KFM : Keyes's figure of merit considering thermal limitation= $\kappa (E_b V_s / 4\pi e)^{1/2}$

BFM : Baliga's figure of merit for power switching = $e m E_g^3$

BHFM : Baliga's figure of merit for high frequency power switching = μE_b^2



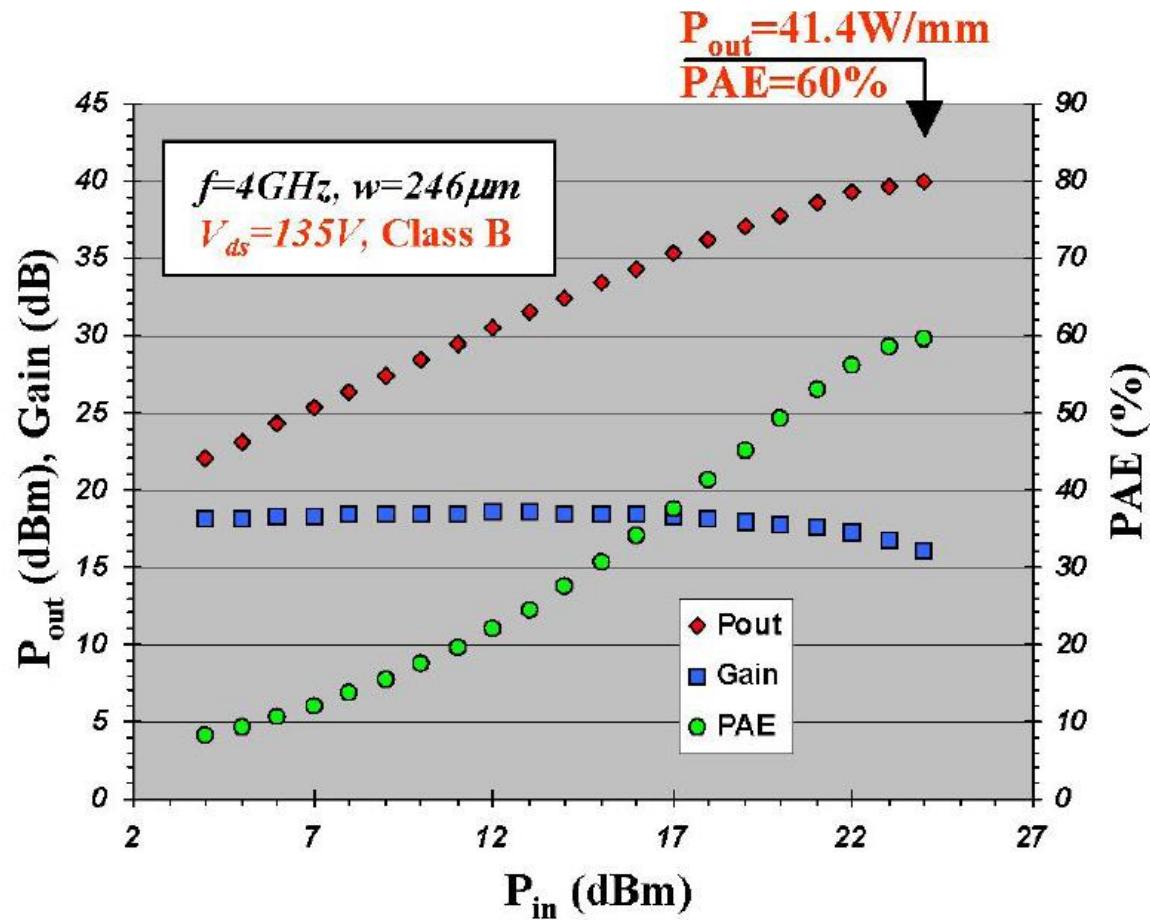
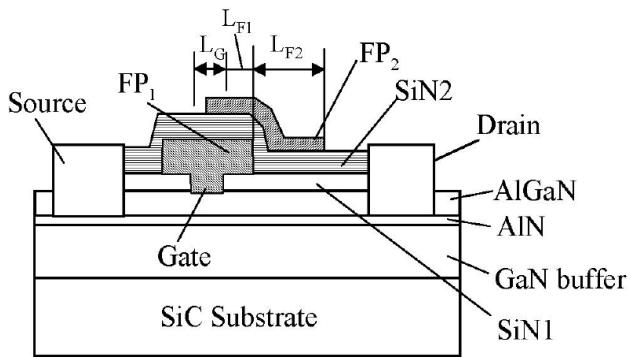
Comparison of R_{on} for Si, SiC and GaN



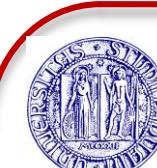
Okumura, JJAP 45,
7565(2006)



GaN-HEMTs capabilities: proven!



[3] Y.-F. Wu, M. Moore, A. Saxler, T. Wisleder and P. Parikh "40-W/mm Double Field-plated GaN HEMTs", Device Research Conference, . 151, 2006



GaN-HEMTs capabilities: proven!

40 W Gallium-Nitride Microwave Doherty Power Amplifier

Kyoung-Joon Cho, Wan-Jong Kim, Jong-Heon Kim*, and Shawn P. Stapleton

School of Engineering Science, Simon Fraser University

*Department of Radio Science & Engineering, Kwangwoon University

the GaN Doherty amplifier yielded a power gain over 12 dB from 1.8 GHz to 2.5 GHz, and 65 % power added efficiency at 40 W peak power. A good linearity of - 55 dBc ACPR was

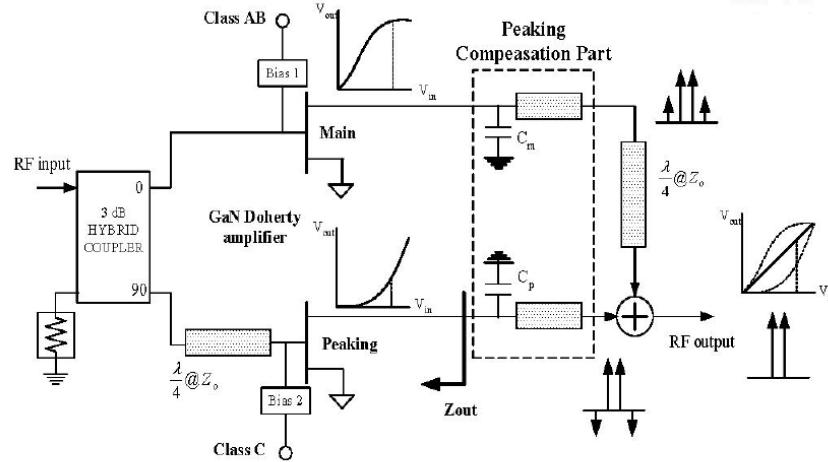


Fig. 1. Simplified diagram for linearity and efficiency of Doherty amplifier

[5] IEEE MTT-S Dig., 2006,
pp. 1895-1898.

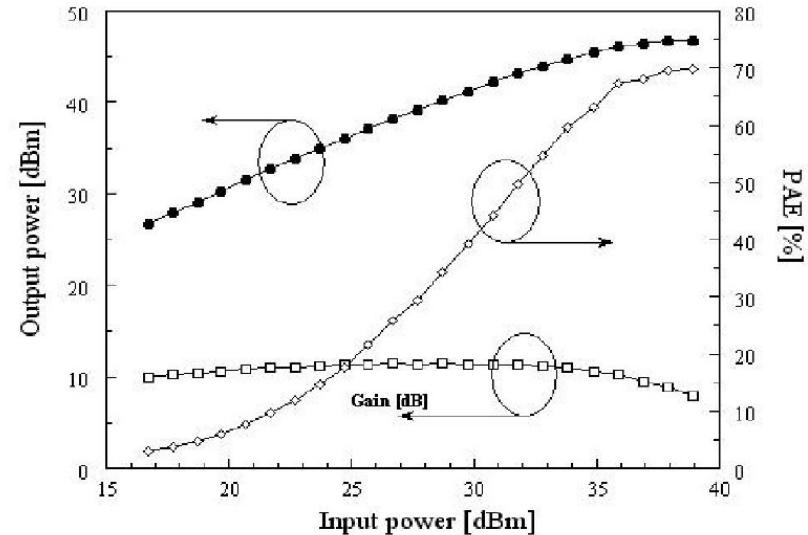
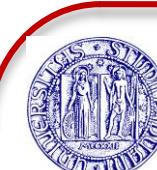


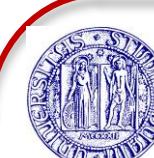
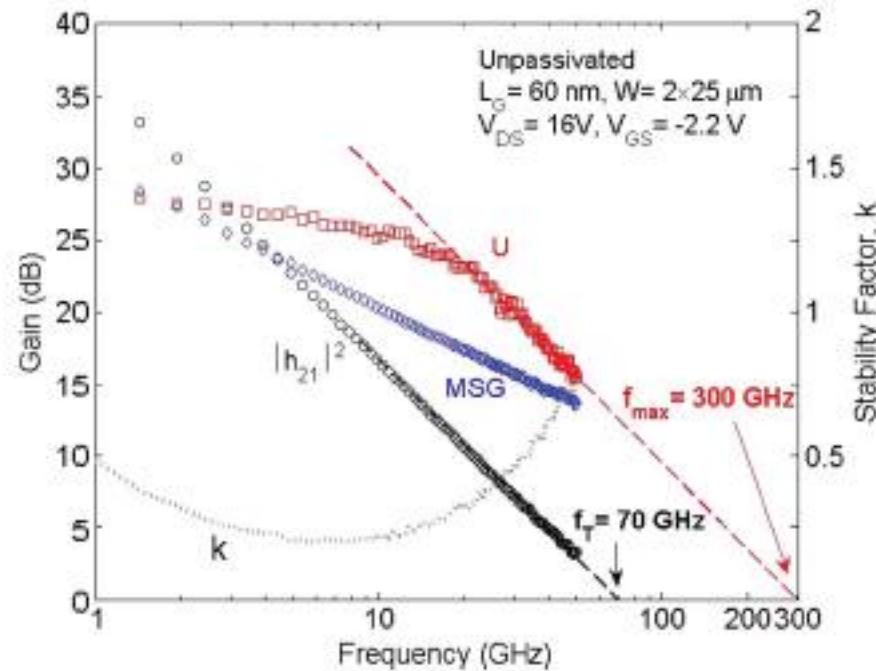
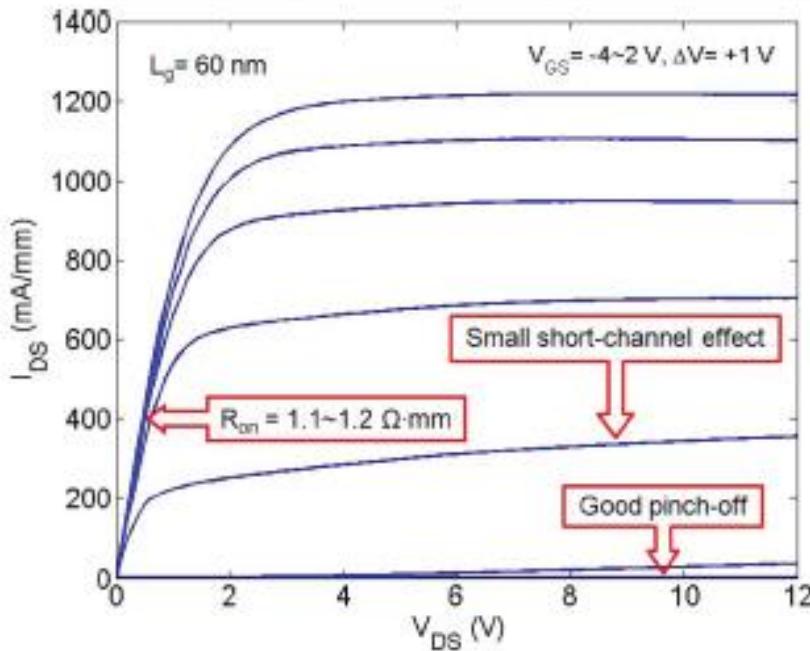
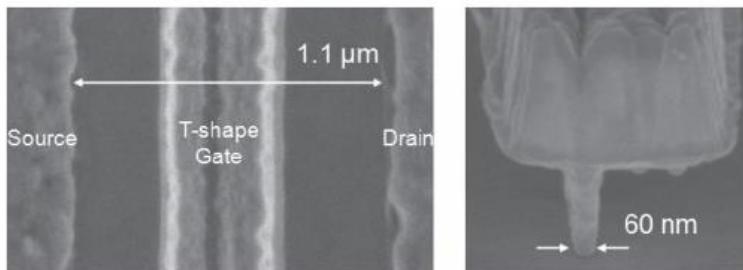
Fig. 6. Measured output power, gain and PAE of a GaN HEMT Doherty power amplifier



GaN-HEMTs capabilities: proven!

AlGaN/GaN HEMT With 300-GHz f_{\max}

Jinwook W. Chung, William E. Hoke, Eduardo M. Chumbes, *Member, IEEE*, and Tomás Palacios, *Member, IEEE*

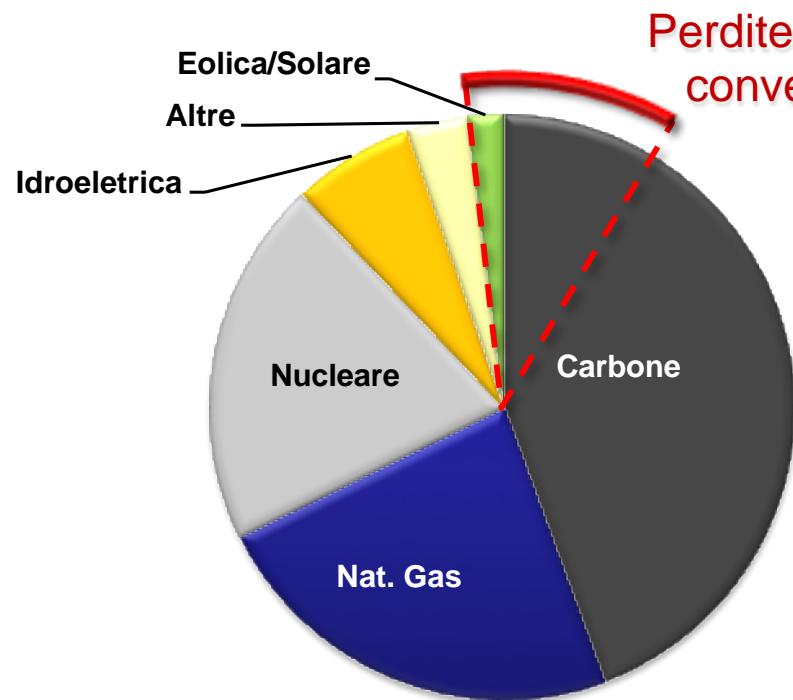


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Efficienza Energetica



Oggigiorno, oltre il 10% dell'energia elettrica globale viene completamente persa a causa dell'inefficienza dei sistemi di conversione.

Chart: EIA U.S. Electric Power Generation

At the moment there are more than 400 nuclear power plants all over the world, which produce about 17% of the world's electricity. <http://www.icjt.org/an/tech/jesvet/jesvet.htm>

Perdere il 10 % di energia elettrica e' equivalente a sperperare l'energia prodotta da più di 200 centrali nucleari.



POWER APPLICATIONS

Primary energy

oil
gas
nuclear
water
wind
solar cell

Power consumption

heat
industry power
information communication
transportation
office
home

Electricity

DC/AC
amplitude
frequency

Si-based inverter devices play important
roles in power conversion process

Efficiency of present inverter : 80~ 90%

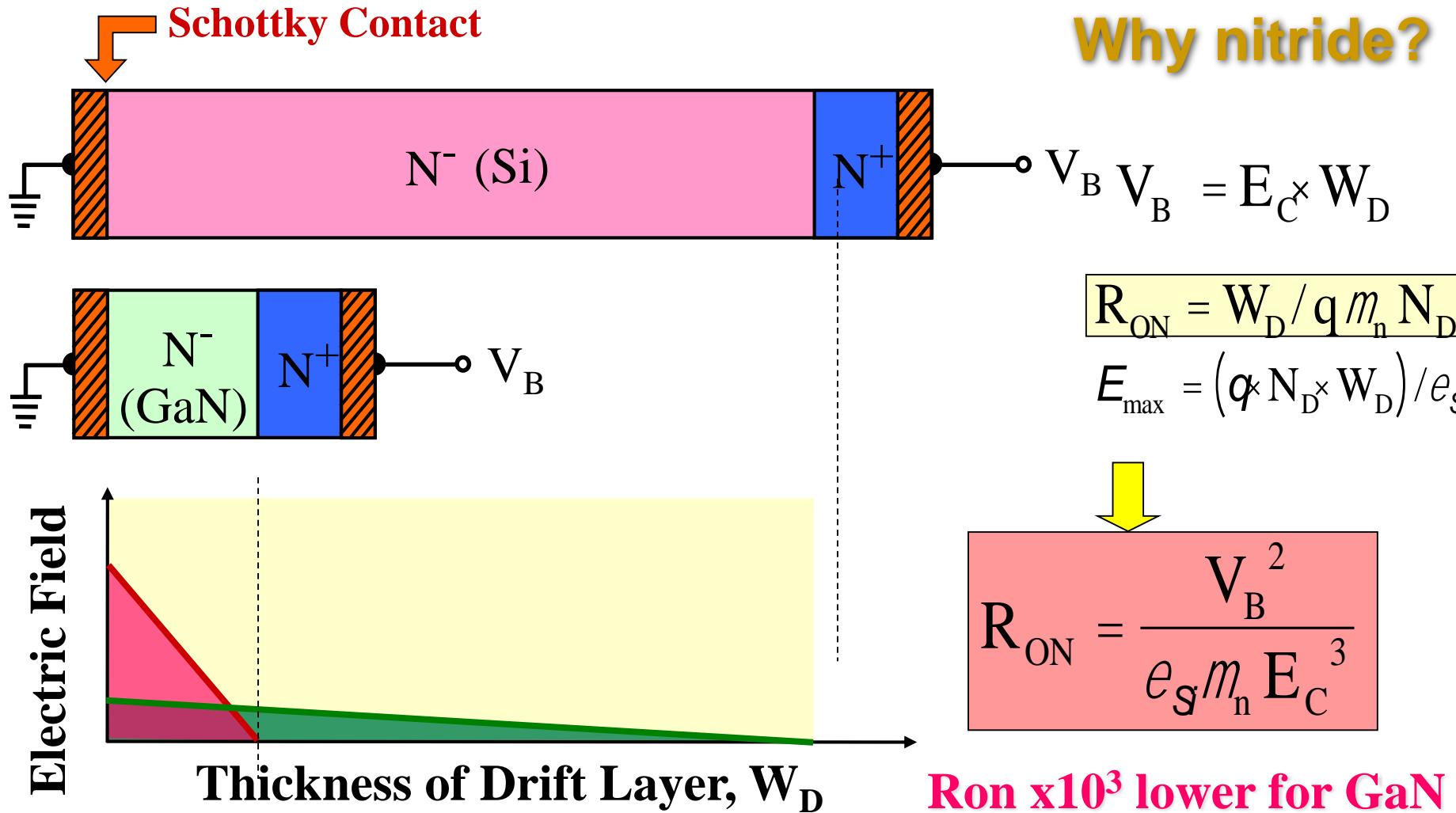
10~20% loss still remains !!

mainly due to the limitation of material properties of Si

Ultra-low loss inverter is a key device for next-generation
energy saving society



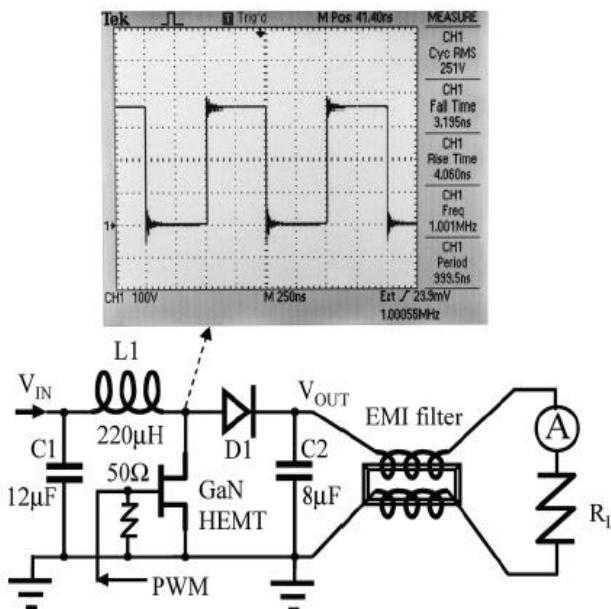
Breakdown Voltage vs On-Resistance



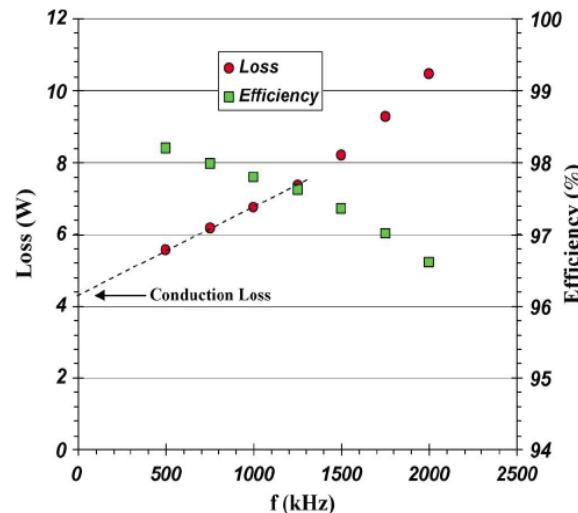
A 97.8% Efficient GaN HEMT Boost Converter With 300-W Output Power at 1 MHz

Yifeng Wu, Matt Jacob-Mitos, Marcia L. Moore, and Sten Heikman

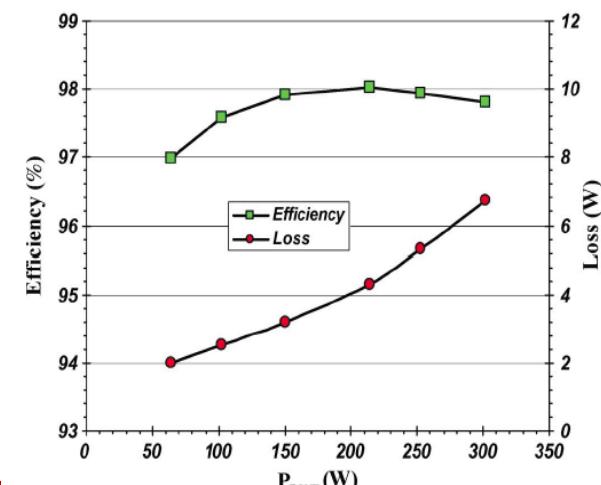
@ 300-W output power



"The peak efficiency of 98% at 214 W is the highest for a hard-switched converter at 1 MHz to date"

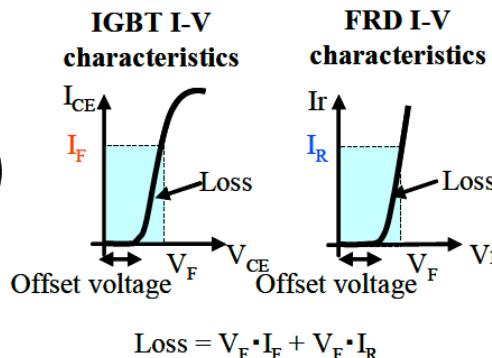
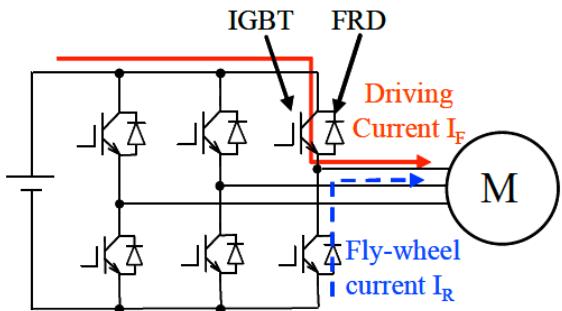


@ 1 MHz

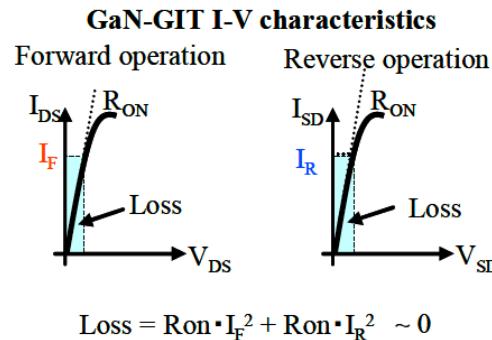
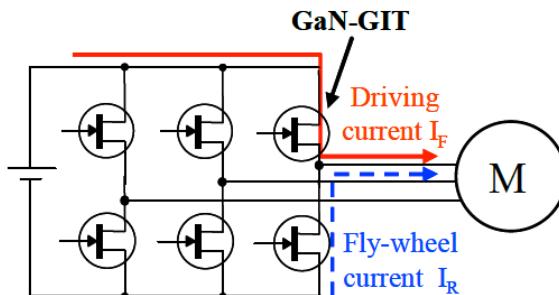


GaN HEMTs for high efficiency power electronics

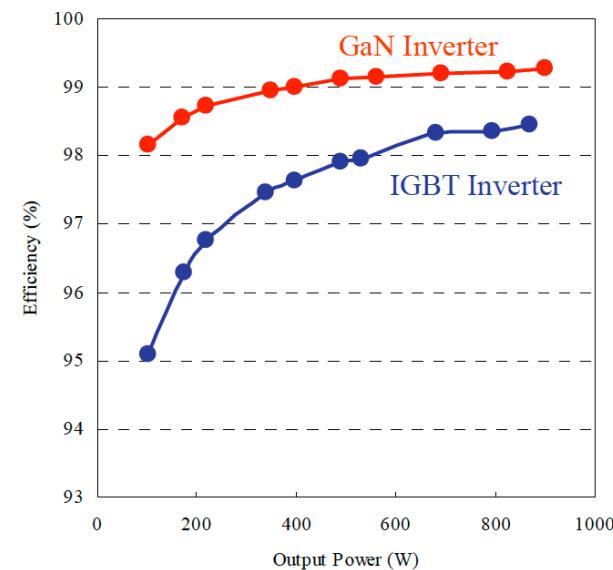
99.3% Efficiency of three-phase inverter for motor drive using GaN-based Gate Injection



(a)



(b)



Panasonic
ideas for life

Morita, T.; Tamura, S.; Anda, Y.; Ishida, M.; Uemoto, Y.; Ueda, T.; Tanaka, T.; Ueda, D.
99.3% Efficiency of three-phase inverter for motor drive using GaN-based Gate Injection
Transistors Applied Power Electronics Conference and Exposition (APEC),
2011 Twenty-Sixth Annual IEEE 2011, Page(s): 481 – 484

Status of the GaN MMIC Technology in Europe

GaN 50 ($0,5 \mu\text{m}$) 0.5..6 GHz

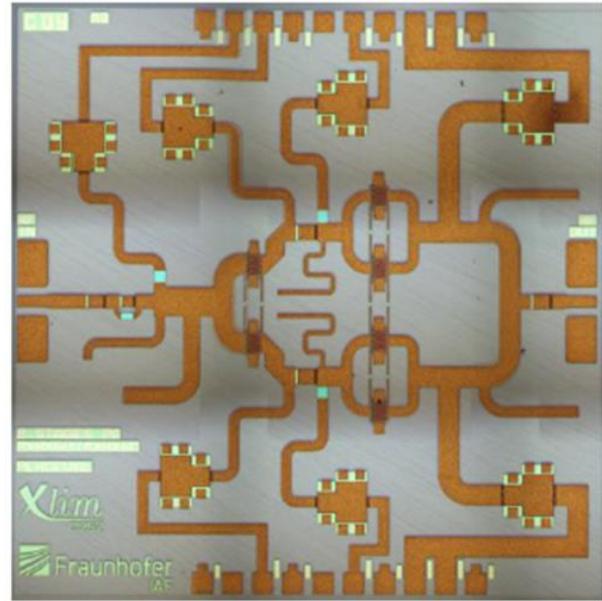
- Products at UMS: hybrid process

GaN 25 ($l_g= 0,25 \mu\text{m}$) to 20 GHz

- Products and further development

GaN 10 ($l_g=0,10 \mu\text{m}$) 20 GHz-94 GHz

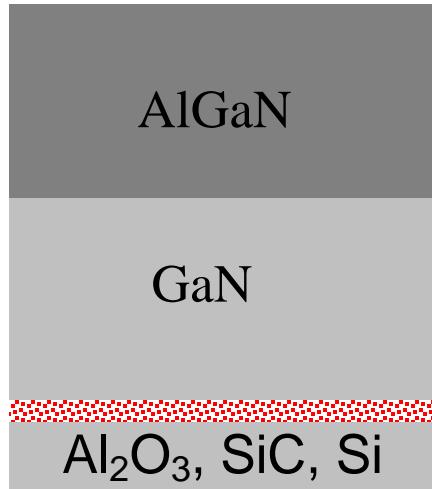
- Development at IAF
- Power electronics at various players



Outline

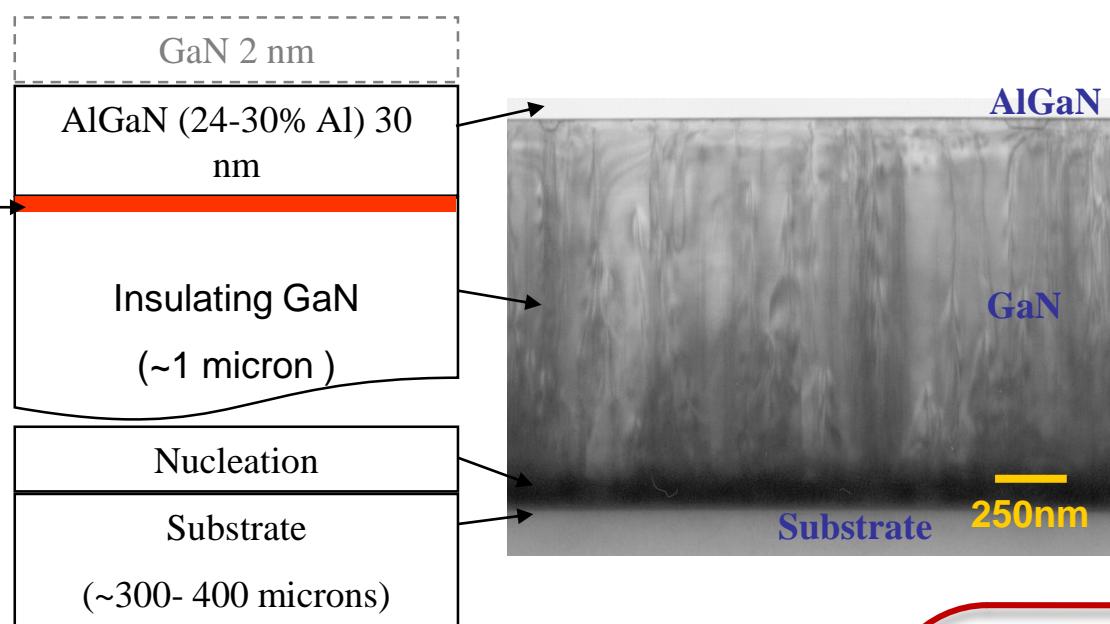
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No GaN substrates available!!



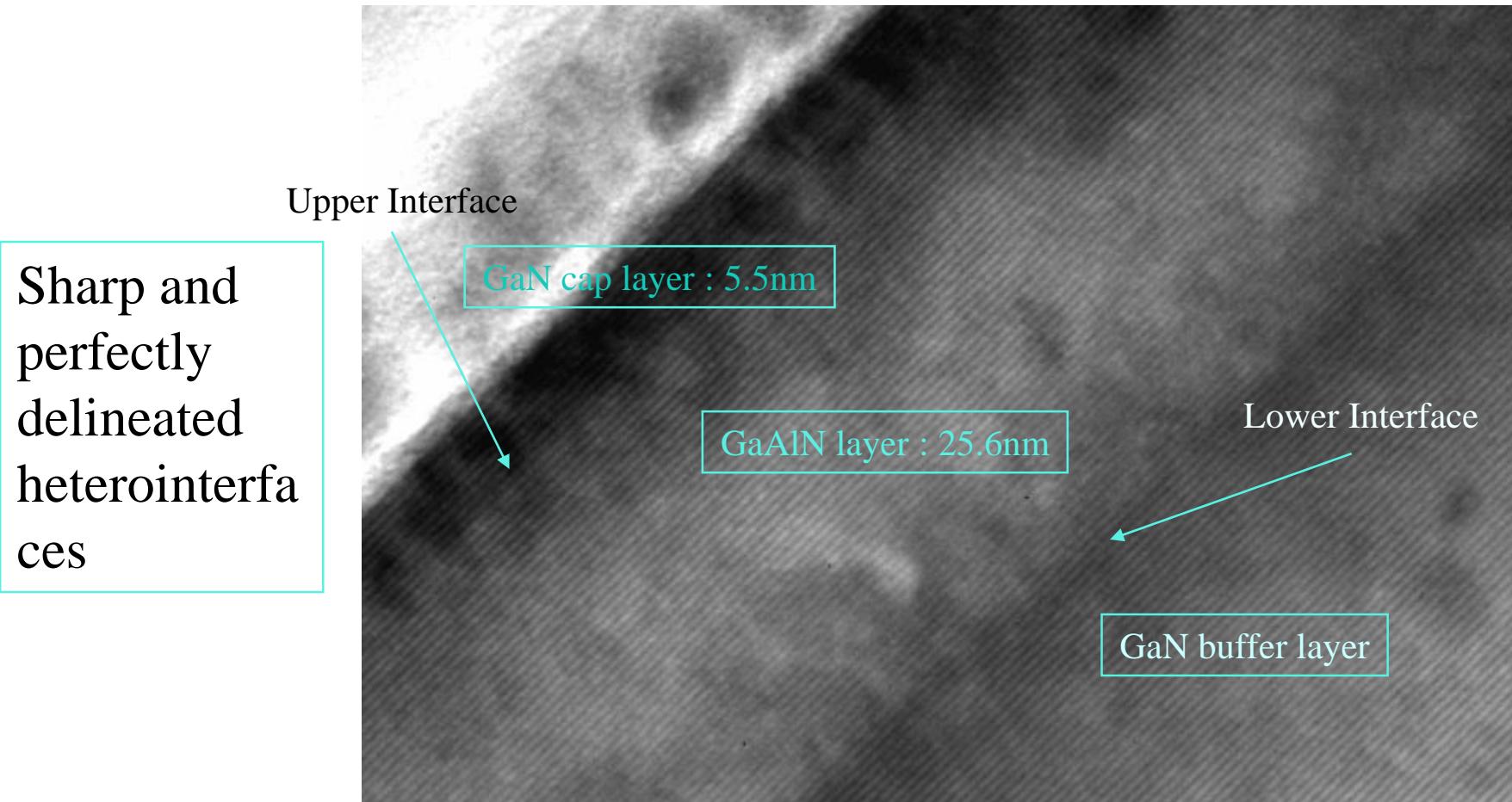
Channel
C Conc. $1 \times 10^{13} \text{ cm}^{-2}$
Resistivity 400-700 ohms / sq

- no native substrate of reasonable size
- heteroepitaxy of (0001) GaN typically on sapphire, silicon carbide or silicon

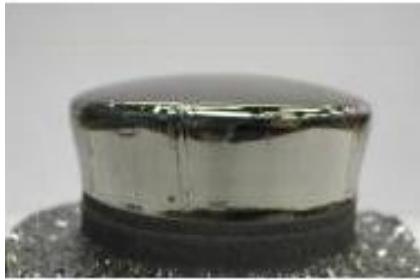


GaN/AlGaN Epitaxy good but not enough!

Good structural quality heterostructure confirmed at the atomic scale



SiC Substrates (2"-4")



- Very expensive (2-5-kE – 4", 6")
- Good thermal conductivity
- Good mismatch

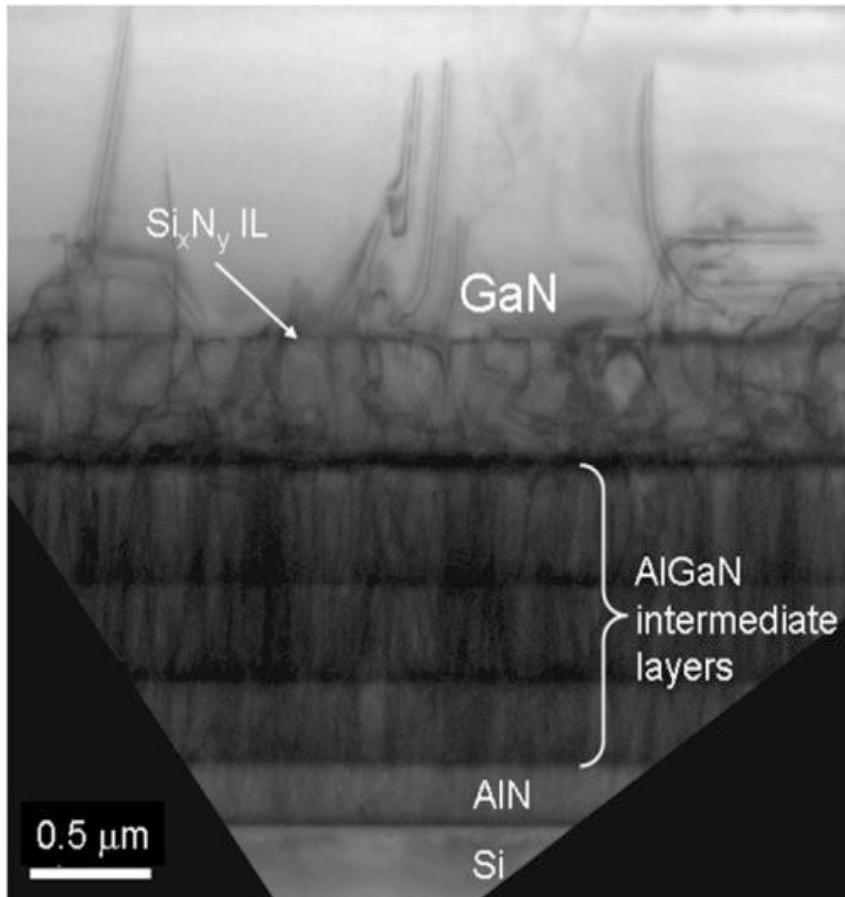


Sapphire Substrates (2"-6")



- Cheap (0,5kE – 2" 4")
- poor thermal conductivity
- Good/poor mismatch

GaN on Si (6" - 8")



The use of Si_xN_y interlayers in GaN grown on sapphire substrates is very successful and a dislocation density reduction by two or three orders of magnitude has been reported. However, it is not straightforward to implement Si_xN_y interlayers in GaN grown on Si due to the large thermal mismatch between GaN and Si.

- Cheap and large diameter
- good/poor thermal conductivity
- bad mismatch



GaN growth always a difficult task!

◆ Substrates for GaN Epitaxy

	GaN Sapphire	GaN n SiC	GaN S.I. SiC	GaN Bulk-GaN	GaN Silicon	GaN 3C SiC Silicon	GaN Glass
Epiwafer providers	TDI Hitachi Cable NTT Kyma OptoGaN AZZURRO	CREE TDI Hitachi Cable NTT	CREE Hitachi Cable NTT Toyoda Gosei AZZURRO IQE,Kopin Picogiga	Sumitomo SEI Kyma LumiLOG Samsung-corning Hitachi Cable AZZURRO	Nitronex AZZURRO Picogiga IMEC IQE NTT DOWA	Toshiba Ceramic (TOCERA)	BlueGlass
Device maker	Lumileds Osram Nichia Toyoda Gosei Velox	CREE Osram	CREE Fujitsu RFMD NXP Freescale NEC, TriQuint	Sony Nichia NEC Toyota	Nitronex OKI TriQUINT MicroGaN, ST, IR, Sanken,Fuji GaN system	R&D	R&D
Application	Blue/white LED, power devices	Blue/white LED	RF devices	Blue/violet laser diode, power devices	Power devices RF,LED	RF devices Power devices	Blue/white LED

Ref.:Website of Yole

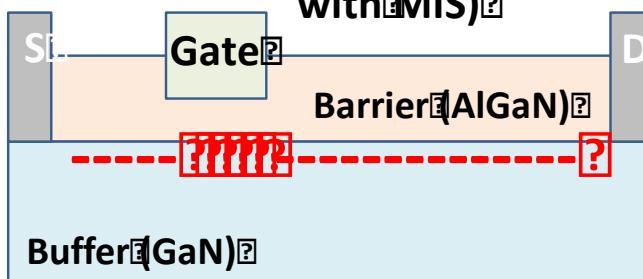
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Normally OFF

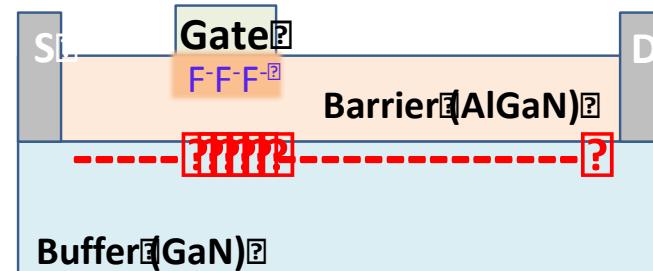
Recess on the Schottky Gate (also with MIS)



- Leakage, Trapping, ...

Oka et al., IEEE EDL 29, 568 (2008)

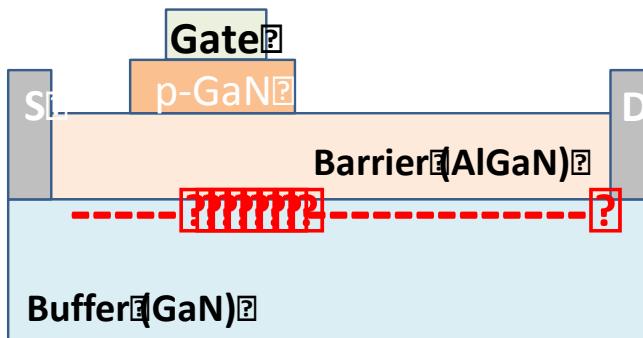
Fluorine Implantation



- V_{th} instabilities, leakage, ...

Feng et al., IEEE EDL 31, 2386 (2010)

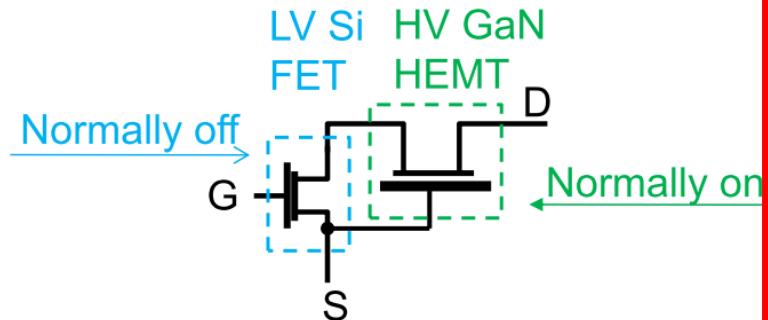
p-type Gate



- Need for p-type, $V_{th} \sim 1.5$ V, ...

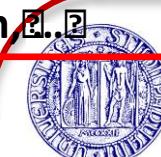
Uemoto et al., IEEE TED 54, 3393 (2007)

Cascode configuration

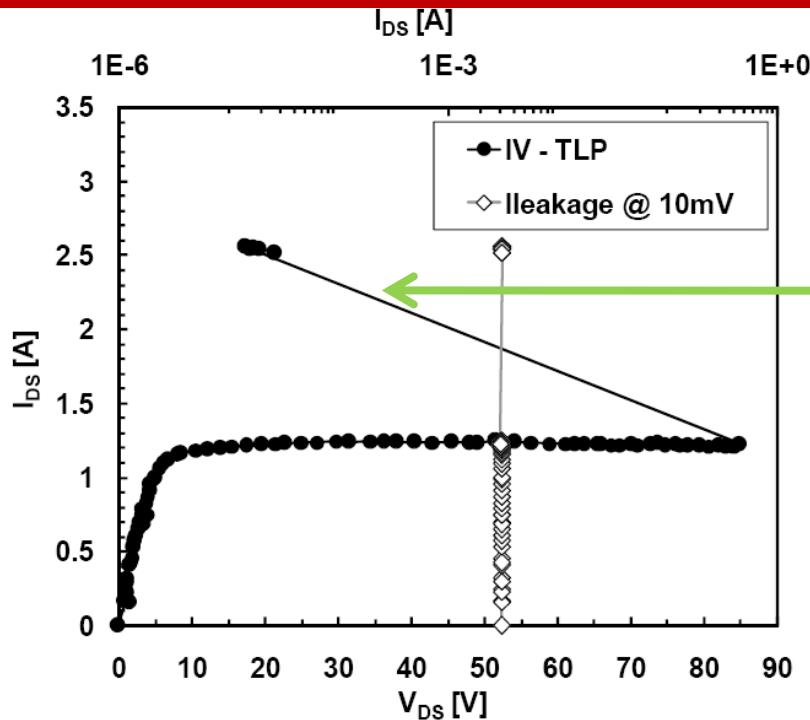


- Combined Si/GaN, MIS gate, ...

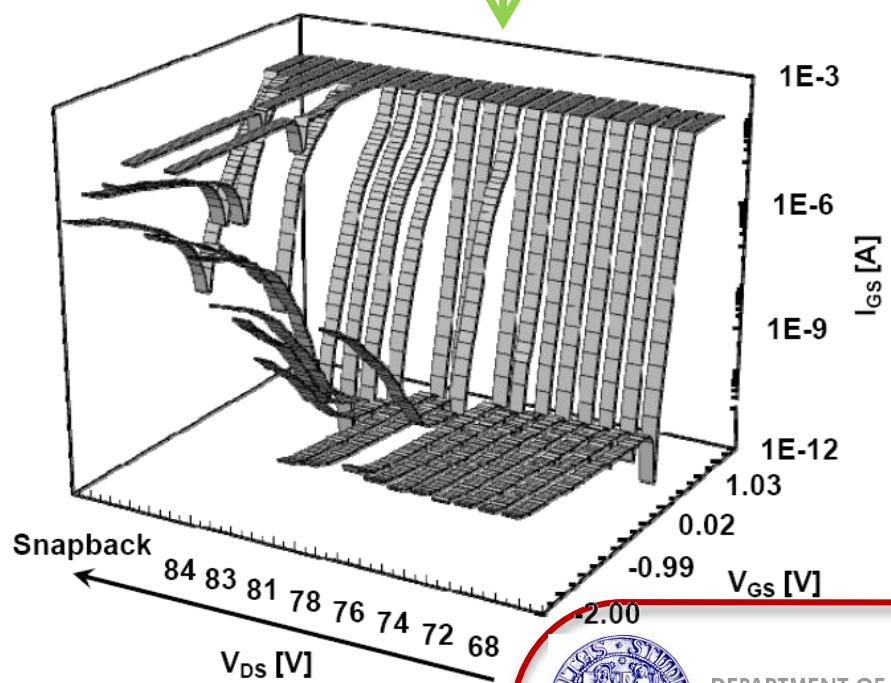
Eg. Transphorm



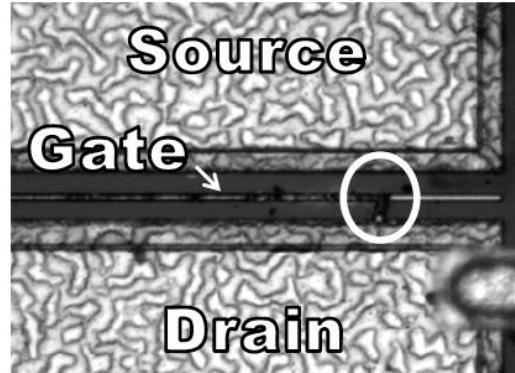
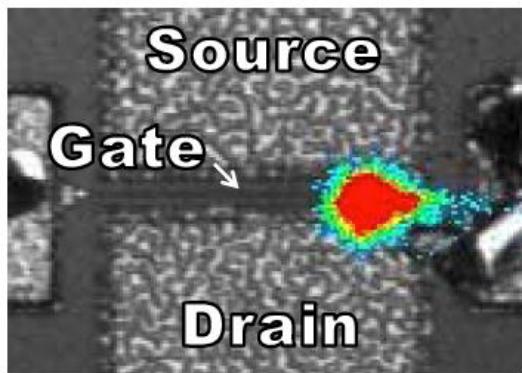
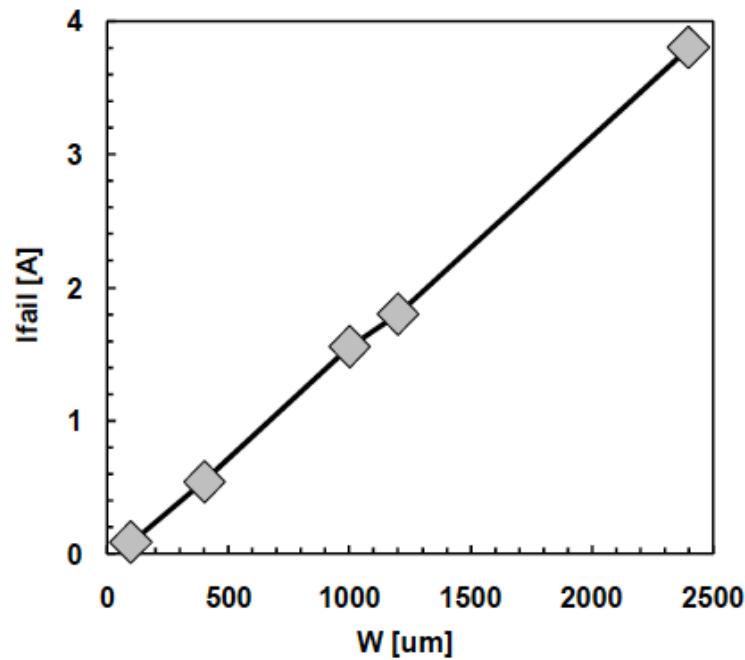
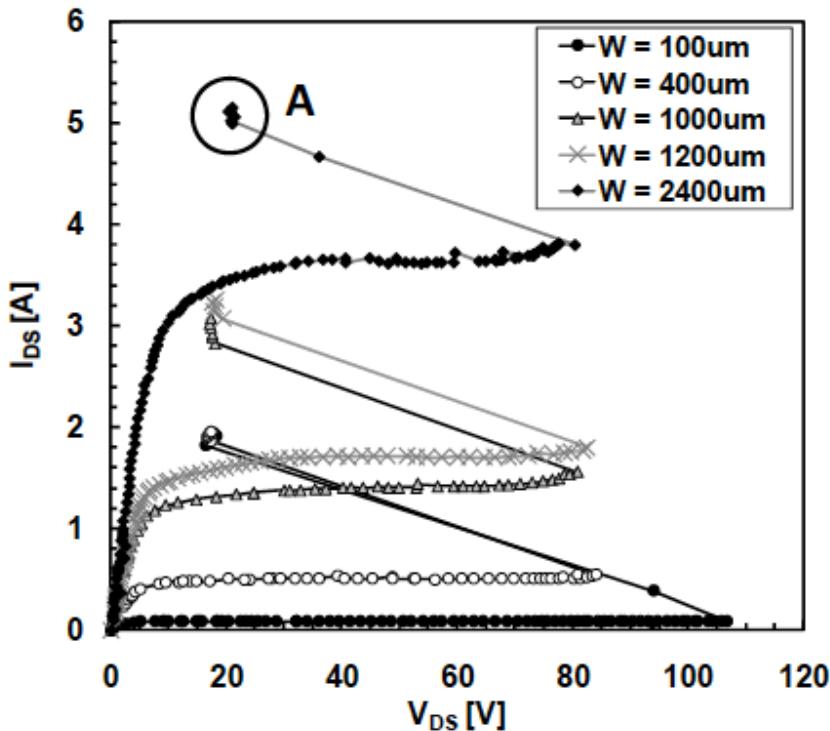
Breakdown measurements



- The breakdown voltage of AlGaN/GaN HEMTs can be evaluated by pulsed ID-VD measurements
- When BDV is reached → Snapback, due to degradation, hot spots
- The junction can degrade even before BDV

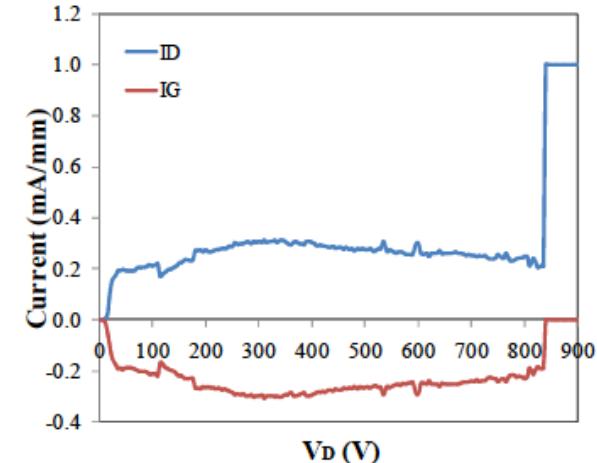
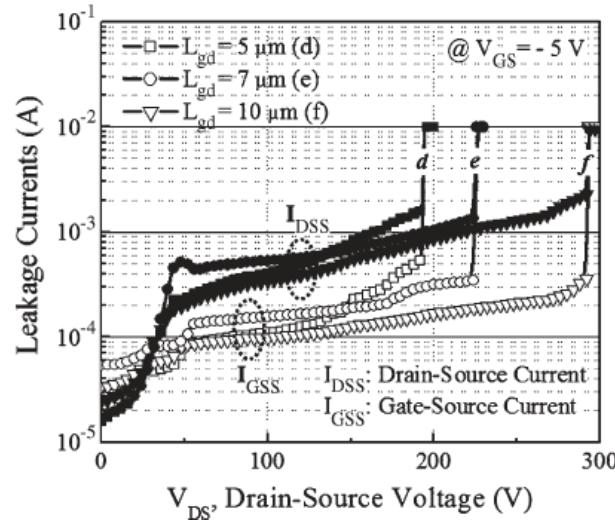
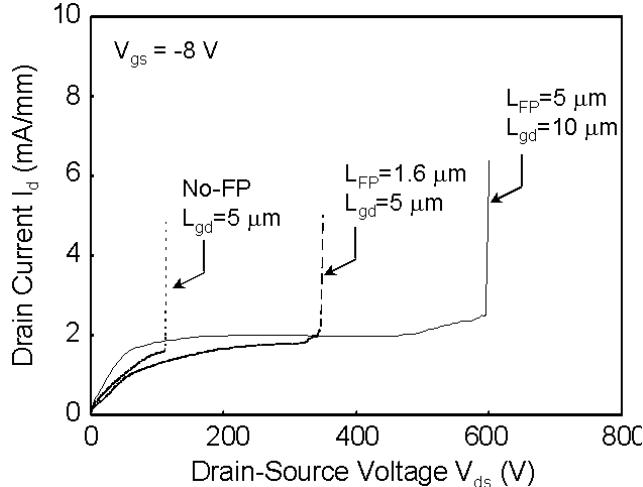


Pulsed ID-VD breakdown measurements



Typical Breakdown in GaN HEMTs

**Breakdown measured in voltage controlled mode is very abrupt.
(no sustainable breakdown present in GaN HEMTs)**



Hwang, ISPSD 2012 3-7
June 2012 - Bruges,
Belgium

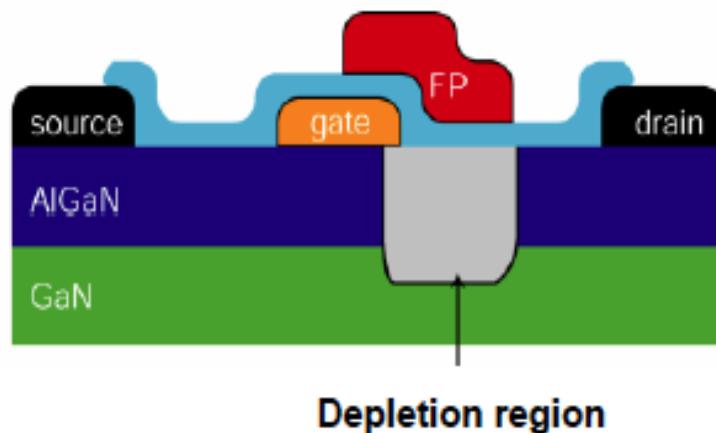
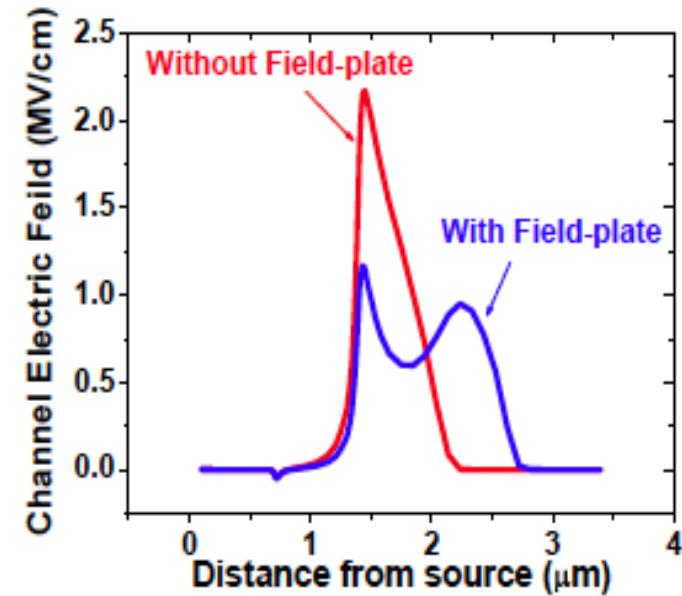
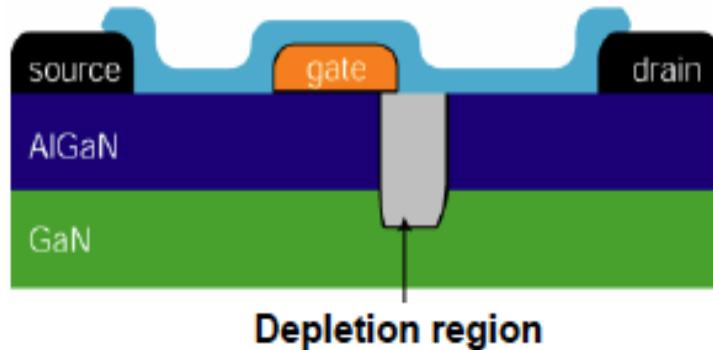
S. Watari et al. IEEE
TRANSACTIONS ON
ELECTRON DEVICES, VOL.
50, NO. 12, DECEMBER 2003

Choi et al. IEEE
TRANSACTIONS ON
ELECTRON DEVICES,
VOL. 53, NO. 12,
DECEMBER 2006



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ENGINEERING
UNIVERSITY OF PADOVA

Field-plate Optimization

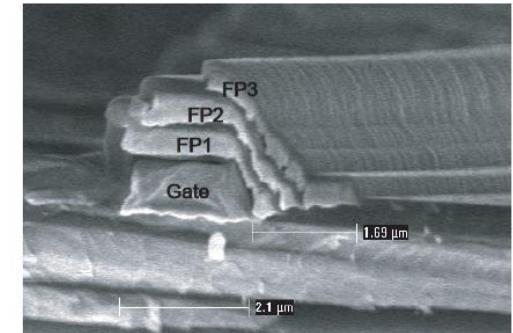
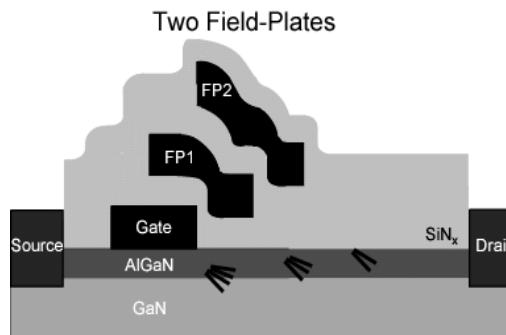
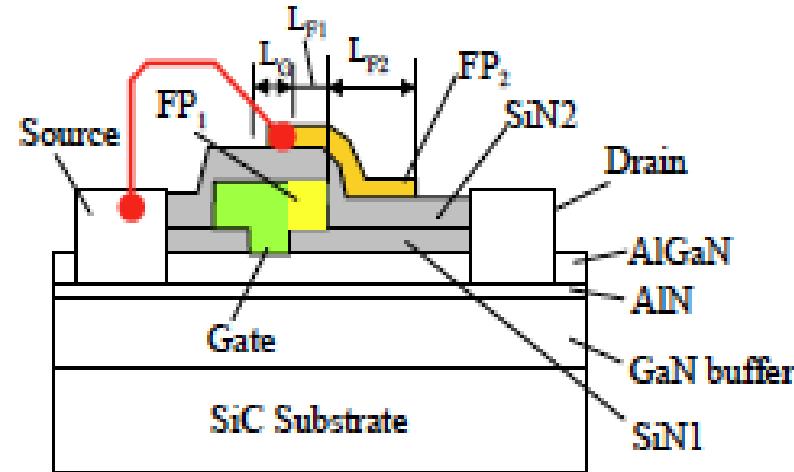
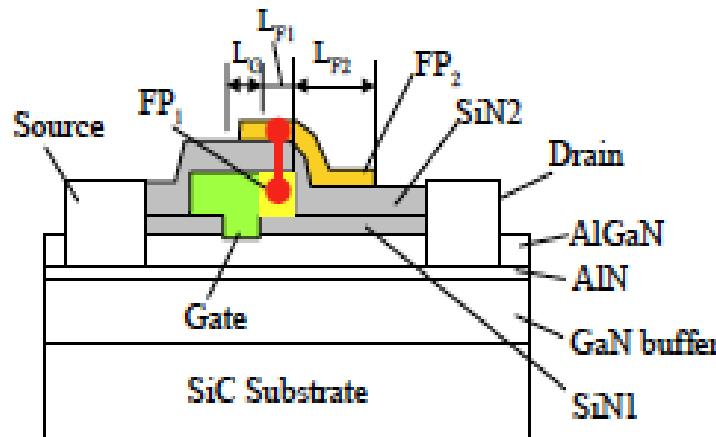
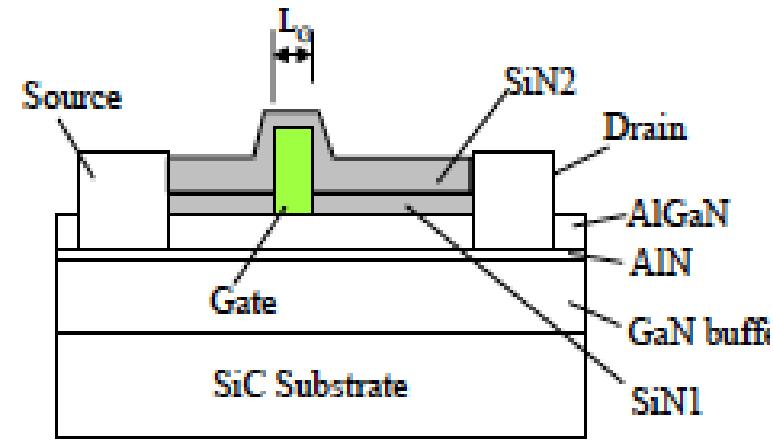


Field-plate reduces electric field

- Increase breakdown voltage
- lower electron injection into traps \rightarrow less dispersion

courtesy: Umesh Mishra, UCSB

Schematics of GaN HEMTs with Various FP Configurations



Very high blocking voltage with compact size

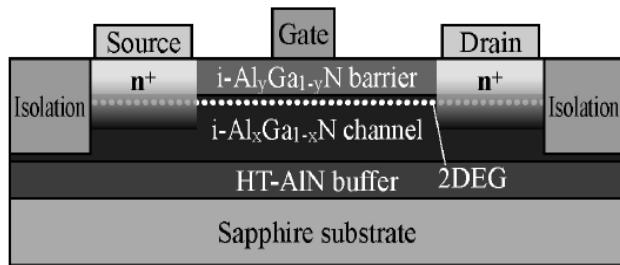
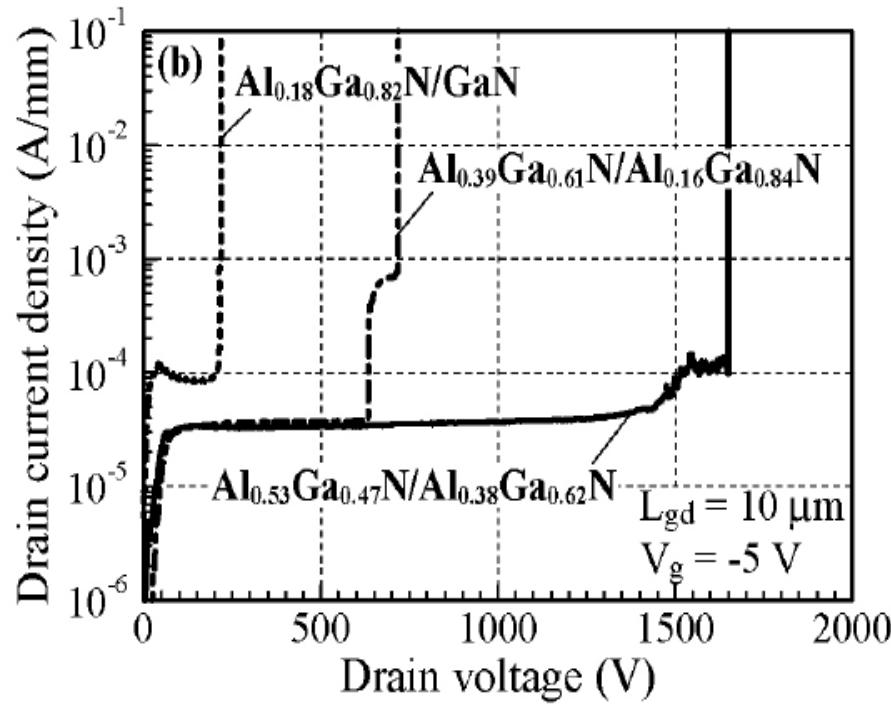
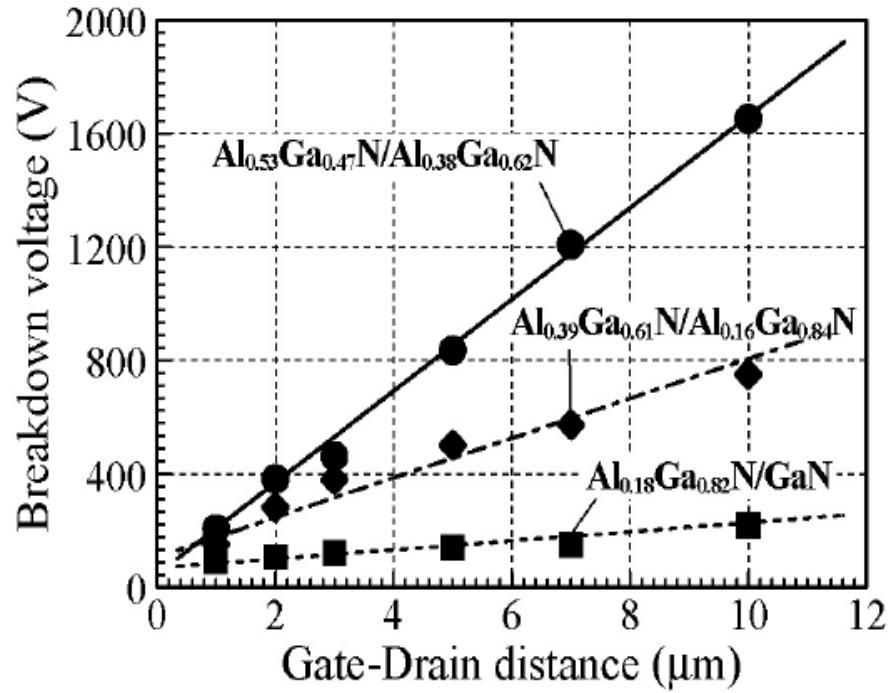


Fig.1 Schematic structure of HEMTs with the hetero-structure consisted of the Al_xGa_{1-x}N channel layer and the Al_yGa_{1-y}N barrier layer (Al_yGa_{1-y}N/Al_xGa_{1-x}N, y > x).



Takuma Nanjo et al, "Remarkable Breakdown Voltage Enhancement in AlGaN Channel HEMTs", IEDM 2007



INVITED REVIEW

Current status and scope of gallium nitride-based vertical transistors for high-power electronics application*

Srabanti Chowdhury¹, Brian L Swenson², Man Hoi Wong³
and Umesh K Mishra⁴

Invited Review

Vertical vs Lateral GaN HEMT

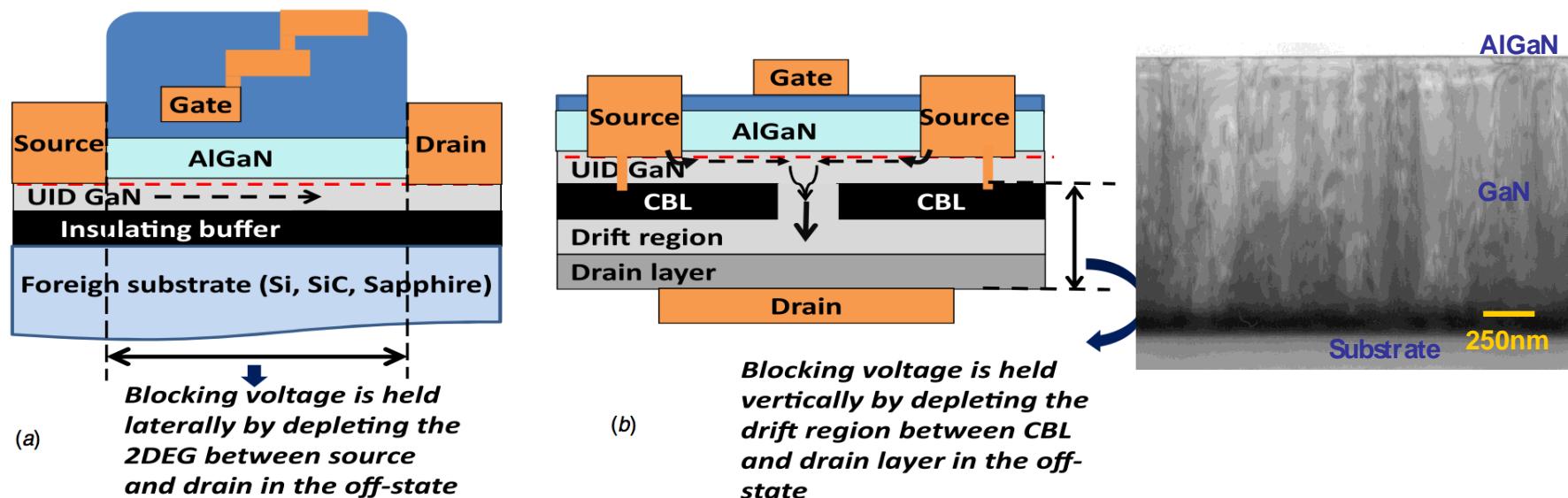


Figure 4. (a) A lateral AlGaN/GaN power HEMT (b) A vertical transistor using AlGaN/GaN layer structure on bulk GaN drift layer and substrate.

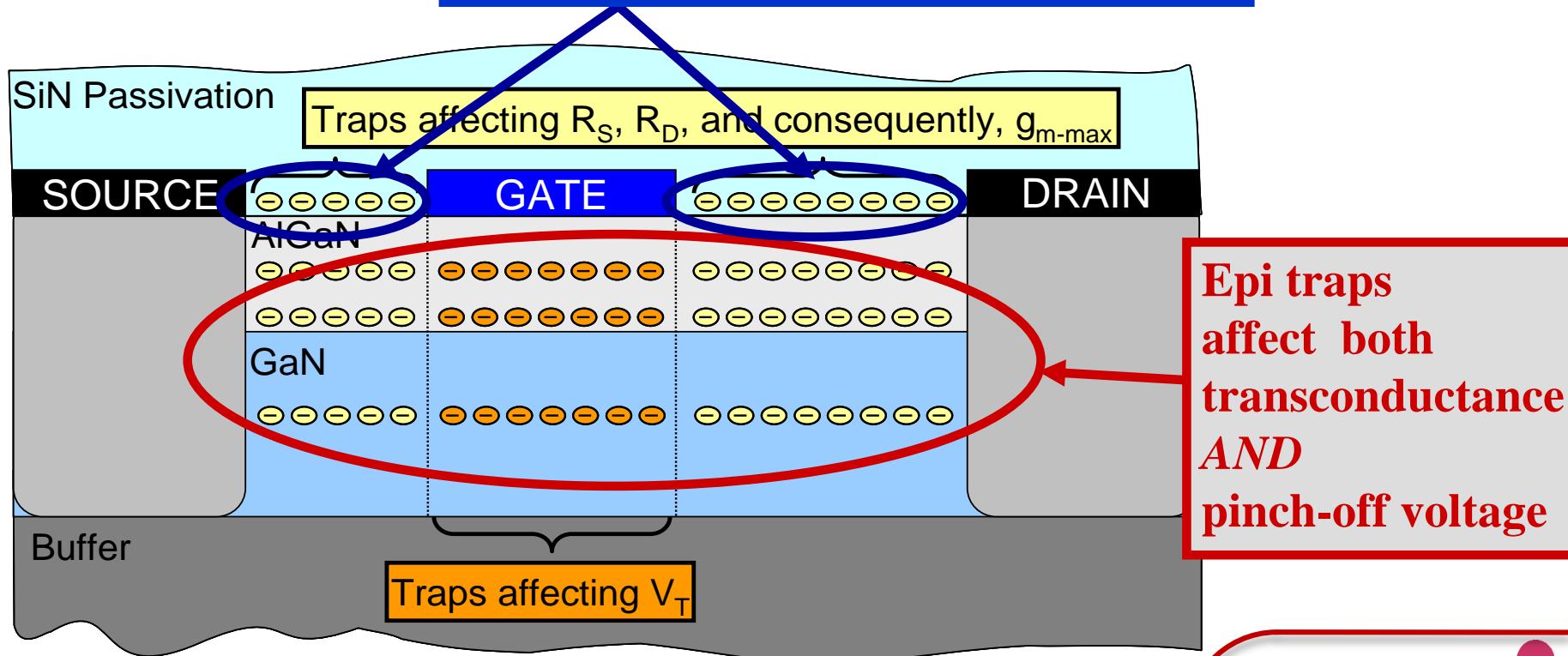
Outline

- Introduction & GaN properties
- Applications opportunities
- Open issues
 - Materials
 - Technology (E-Mode, Breakdown, Vertical vs lateral)
 - Parassitic & Reliability
- GaN Activities within IU.NET
- Conclusions

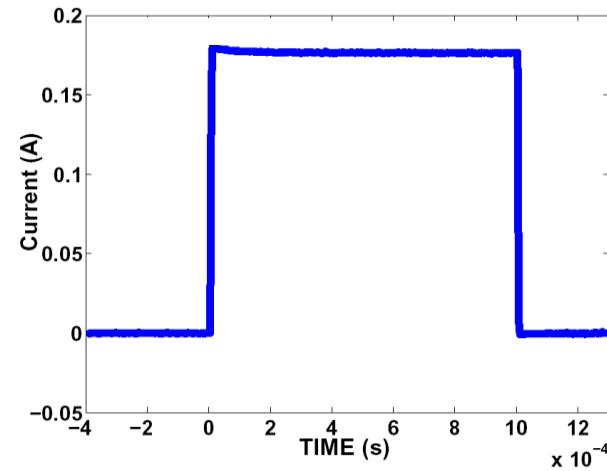
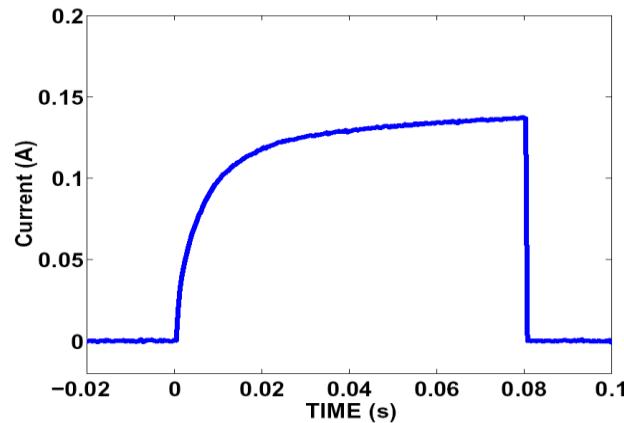
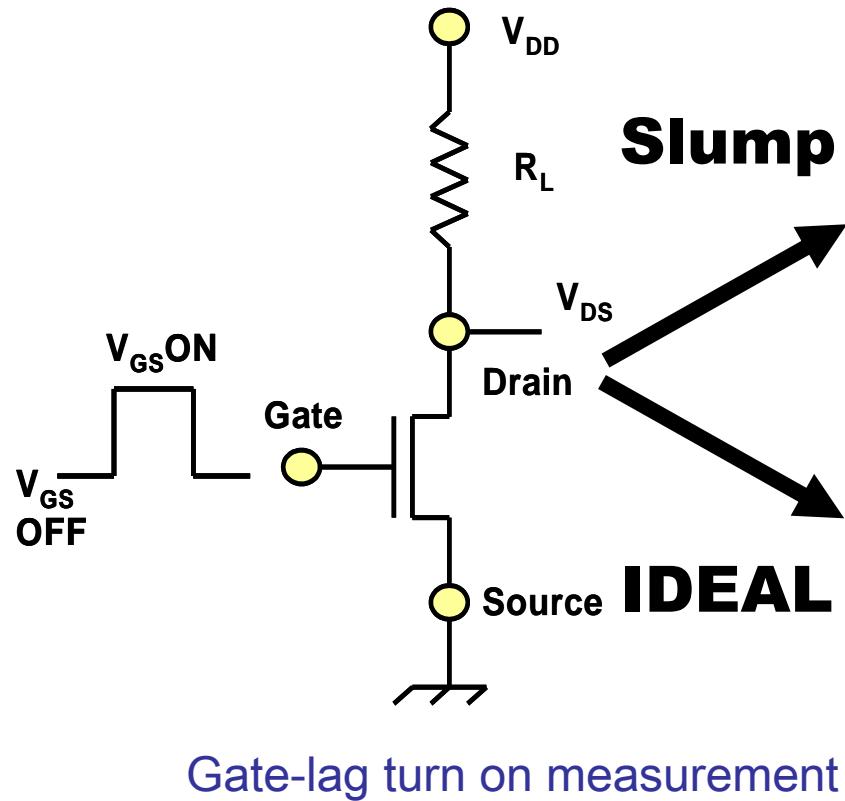


Parasitic and Reliability (UniPD)

surface traps affect transconductance through series resistance increase
they can not affect pinch-off voltage, unless L_g is fairly short

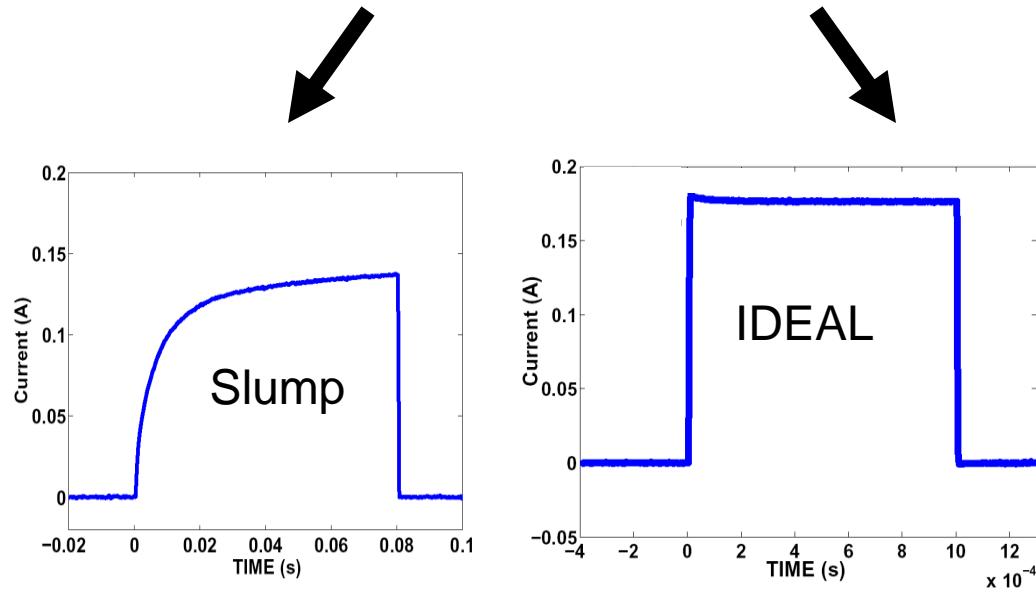
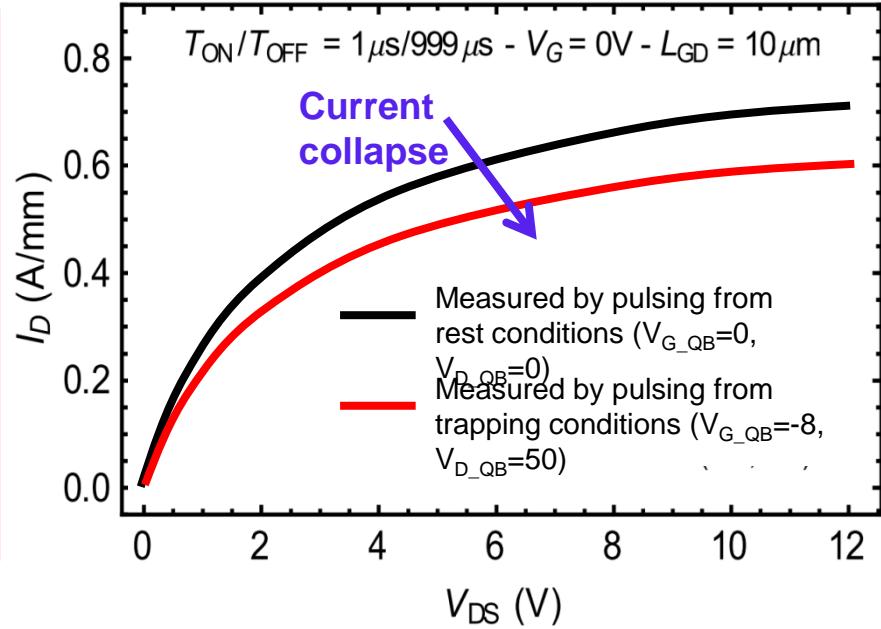
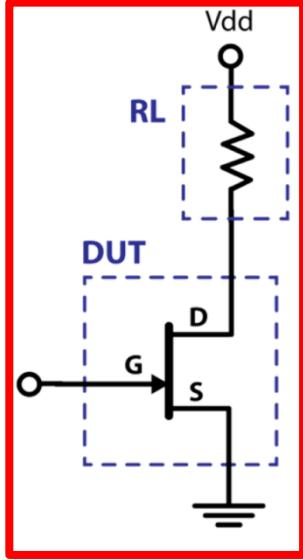
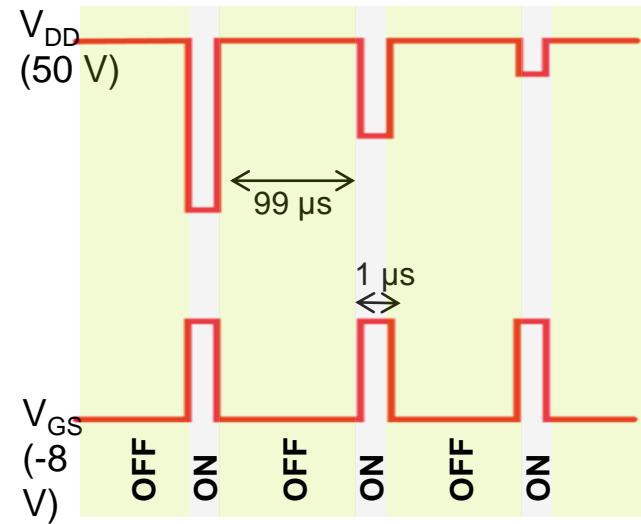


Parassitic and Reliability (UniPD)



[7] STEVEN C. BINARI, et al., "Trapping Effects in GaN and SiC Microwave FETs", PROCEEDINGS OF THE IEEE, VOL. 90, NO. 6, . 1048- 1058, JUNE 2002

Parassitic and Reliability (UniPD)



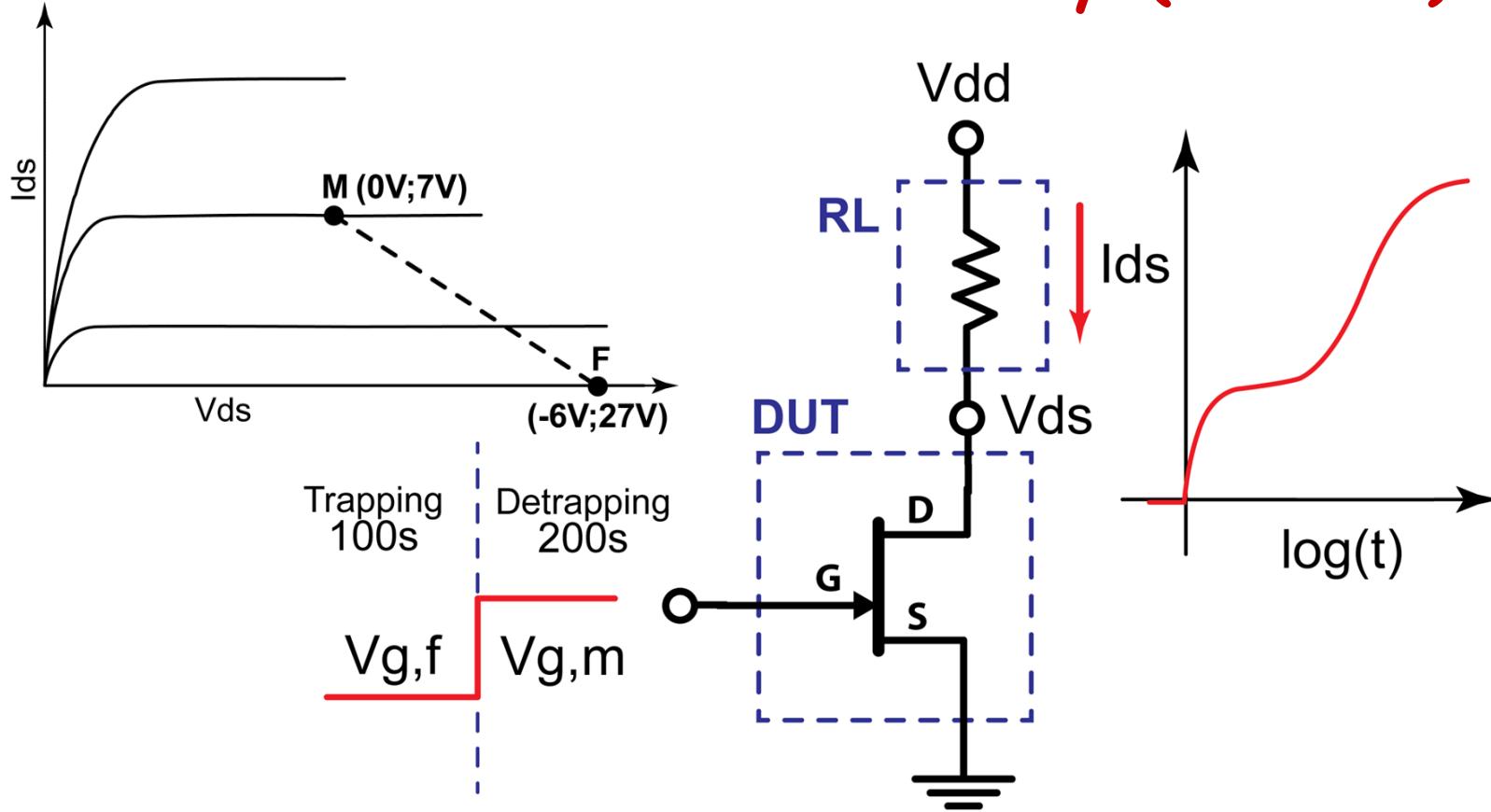
Current collapse \rightarrow recoverable decrease in drain current induced by trapping

When a HEMT is switched on after a trapping phase \rightarrow current shows an exponential transient before reaching steady-state value (de-trapping transient)

The same happens if ID-VD curves are measured from several QBPs

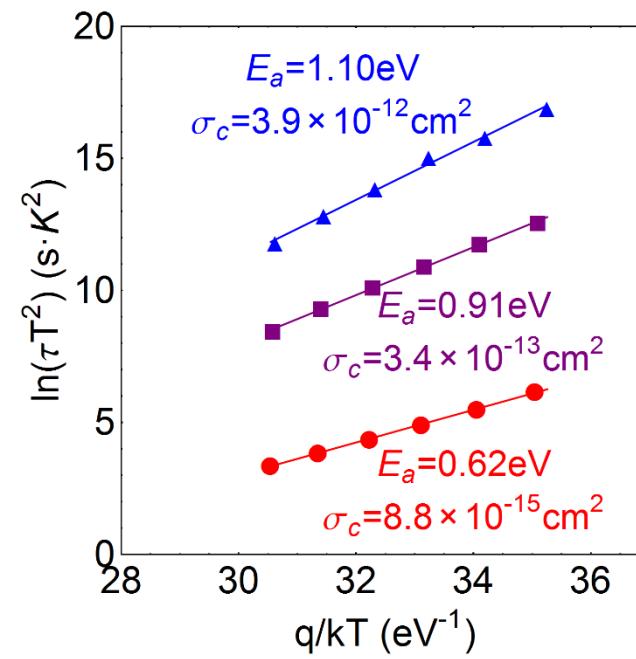
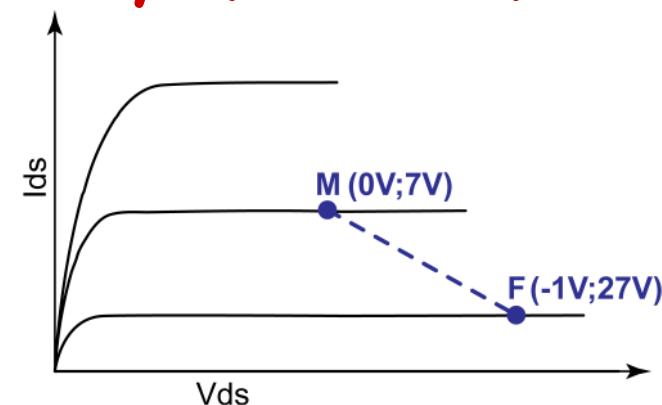
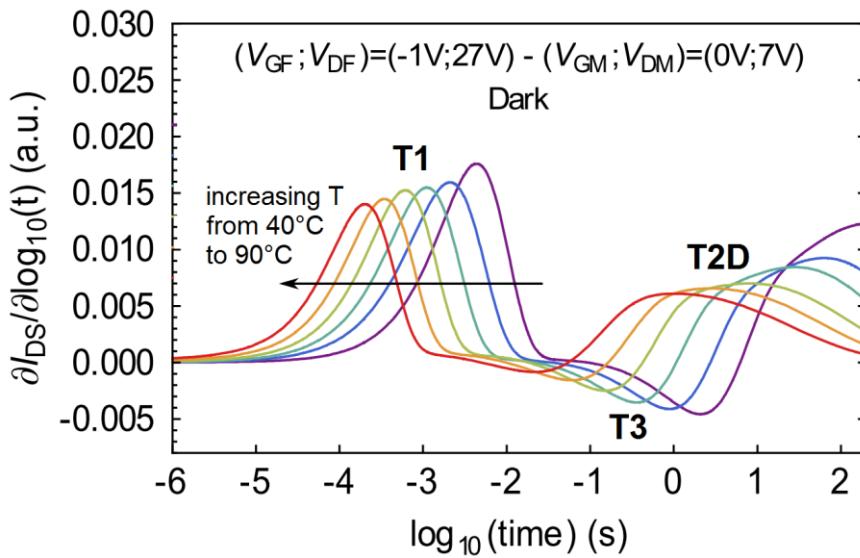
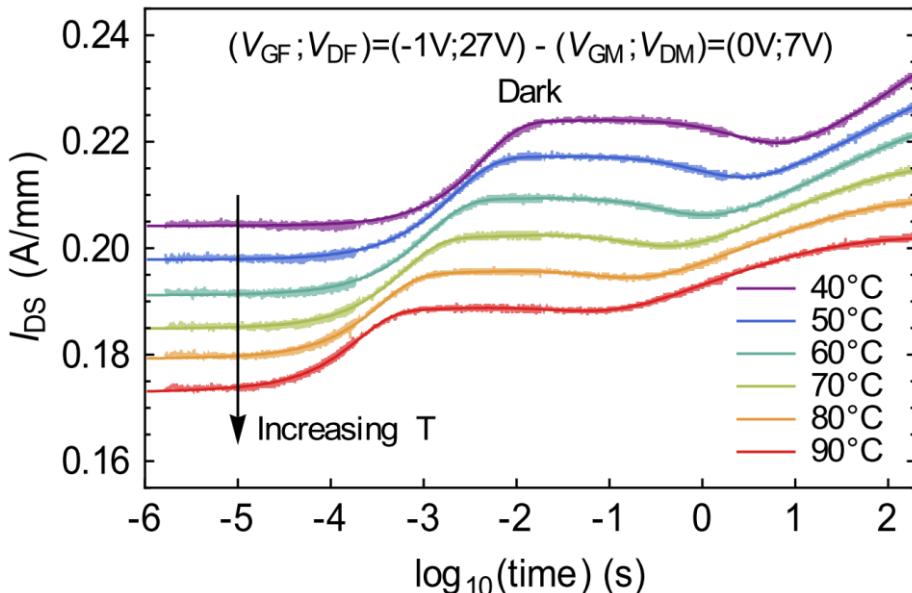


Parasitic and Reliability (UniPD)



The Drain Current Transient analysis comprehensively investigate the **time evolution of carrier (de)trapping processes**. The **deep-levels signatures – activation energies and capture cross-sections – and their localization** can be achieved by performing the measurements under different bias conditions and different base-plate temperatures.

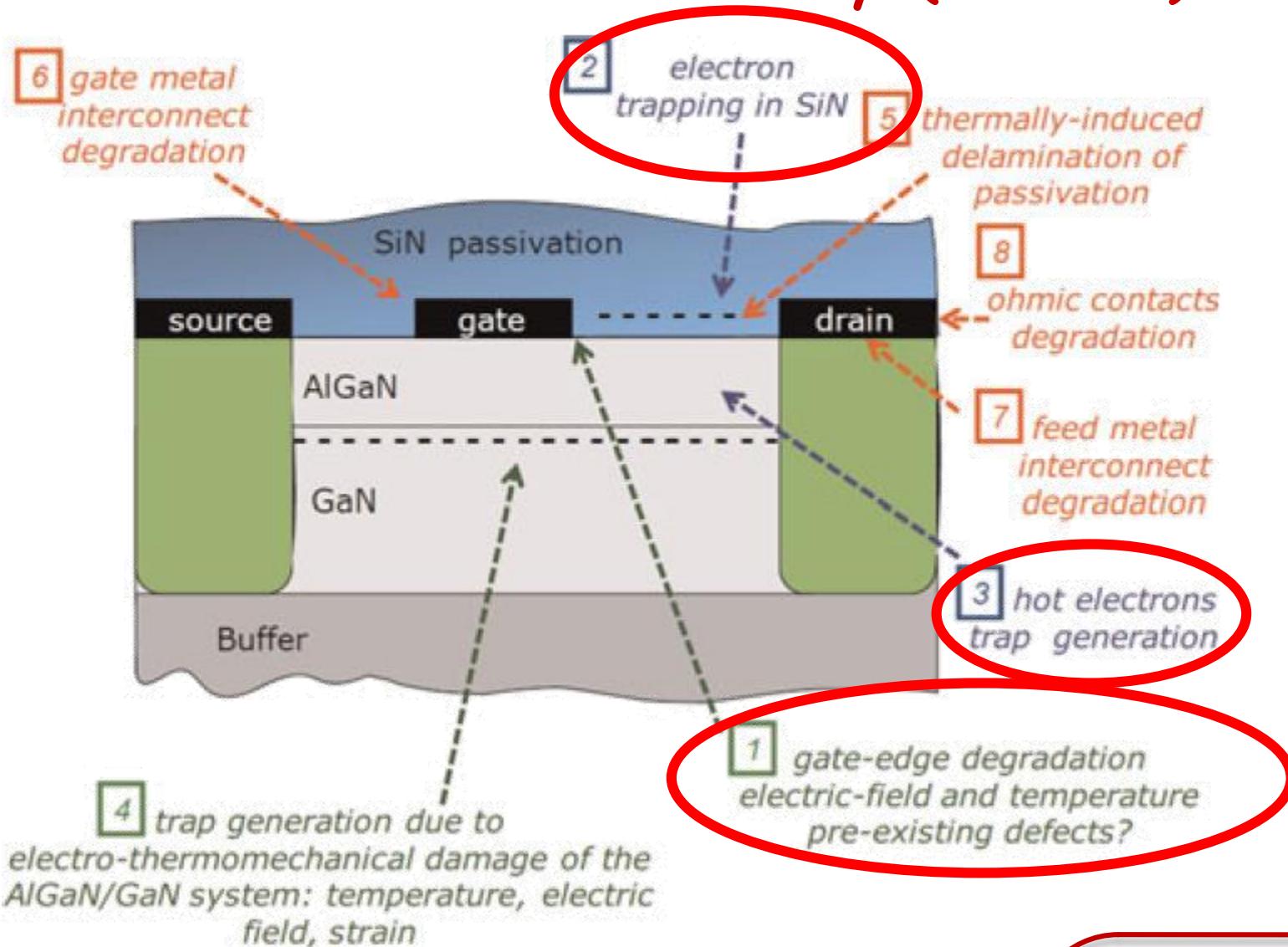
Parasitic and Reliability (UniPD)



D. Bisi *et al.*, "Deep-Level Characterization in GaN HEMTs-Part I: Advantages and Limitations of Drain Current Transient Measurements," *IEEE Trans. Electr. Dev.* 60, 3166, 2013.

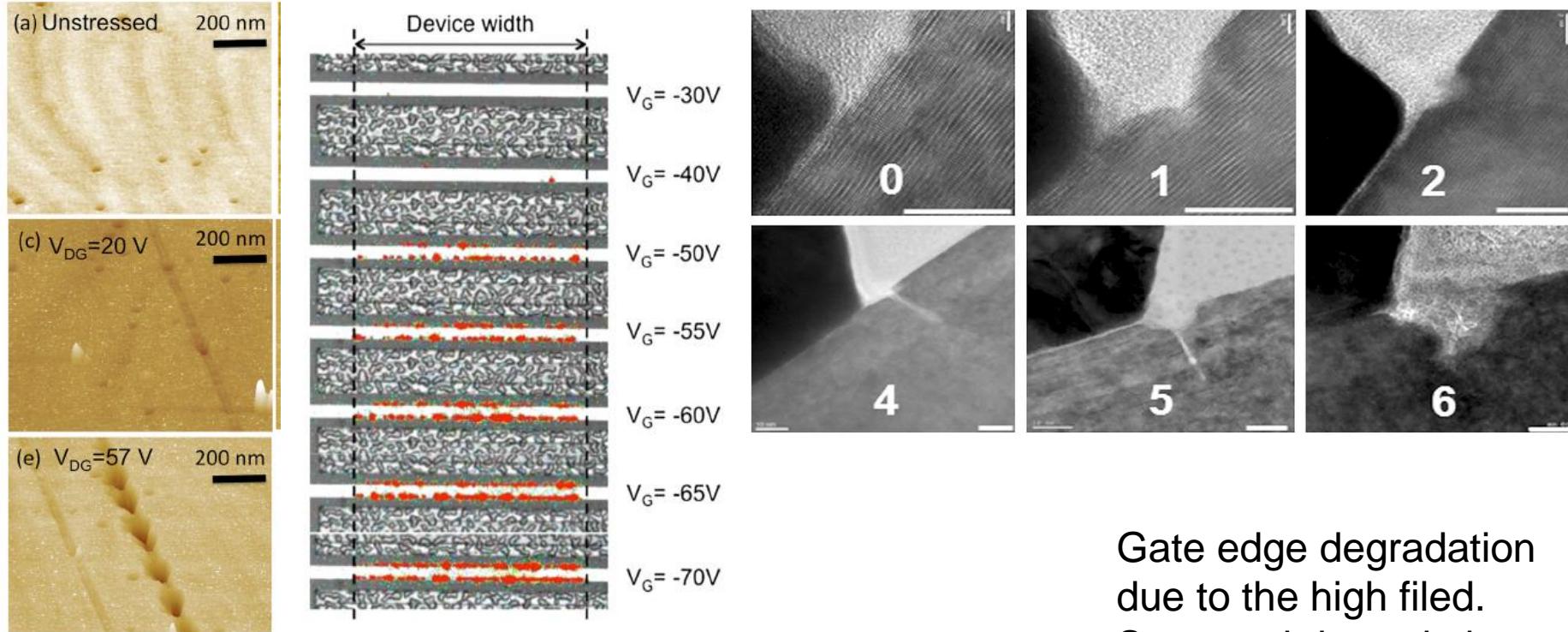


Parasitic and Reliability (UniPD)

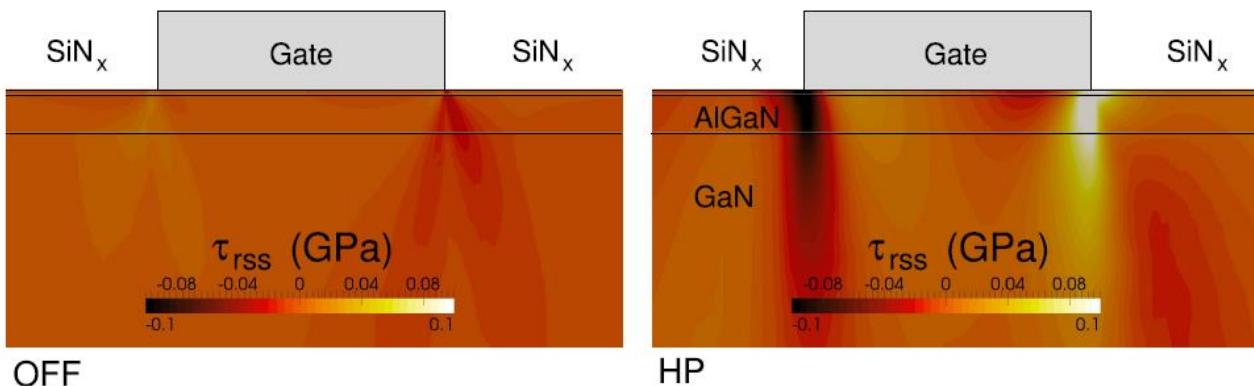


Meneghesso et al., Int. Jour. of Microwave and Wireless Technologies, 2010, 2(1), 39–50

Parasitic and Reliability (UniPD)

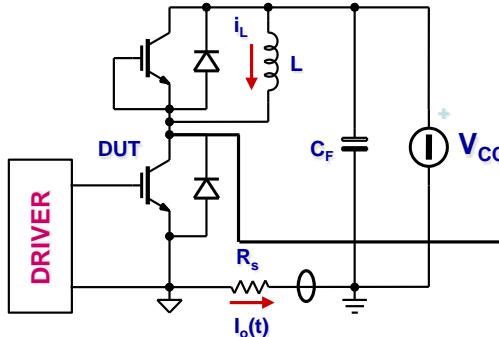


Gate edge degradation
due to the high field.
Structural degradation
has been identified
(Traps, percolation
path, increase in
resistance)

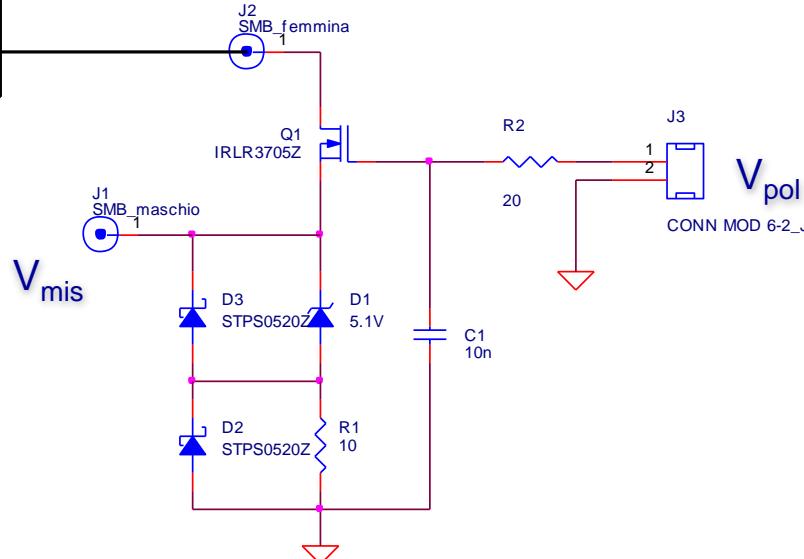


Activity at Power Electronic (PEL) Group - UniPD

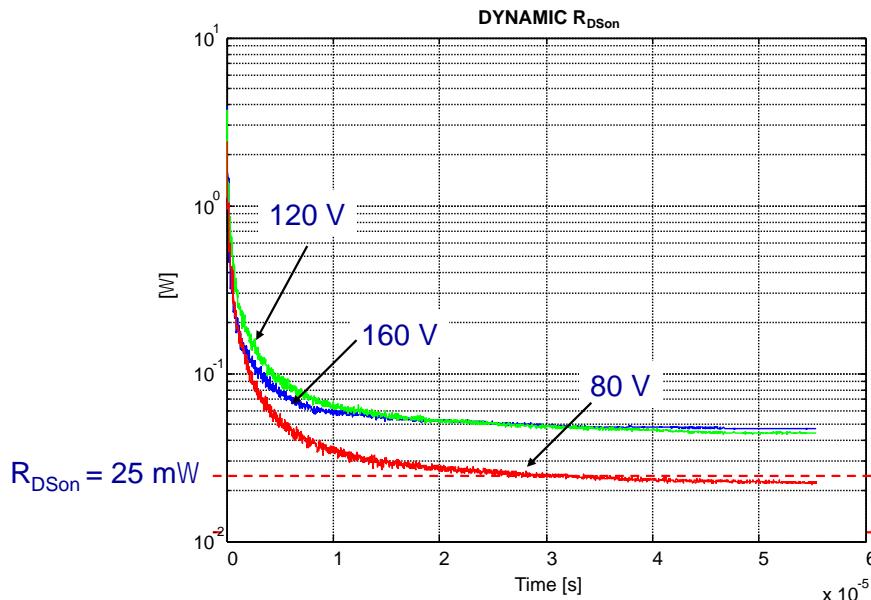
P. Tenti,
L. Rossetto,
G. Spiazzi,
S. Buso,
P. Mattavelli
L. Corradini



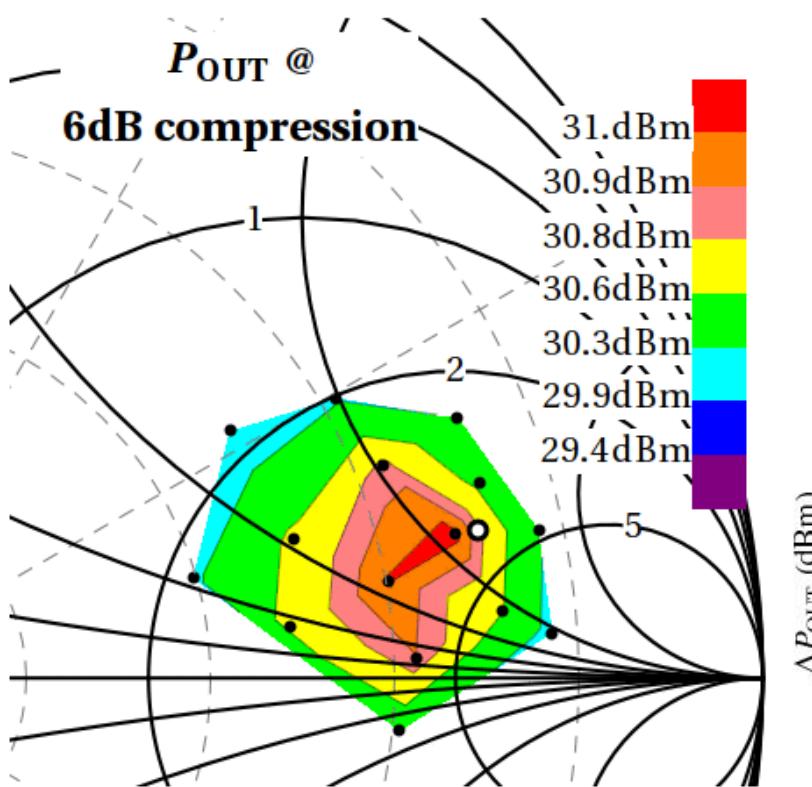
FR9N20DPBF per clamp da 200V



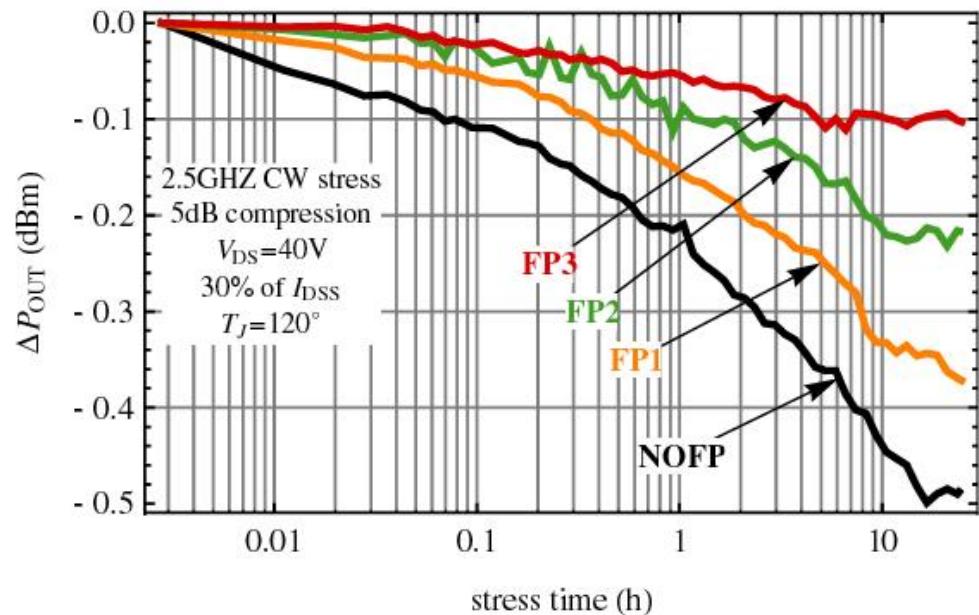
- Characterization of commercial GaN MOSFET power devices
- Design and implementation of optimized switching cells for device parameter in-circuit characterization
- Realization of a Pont of Load (PoL) converters using GaN devices



GaN HEMTs RF Characterization and Stress Tests



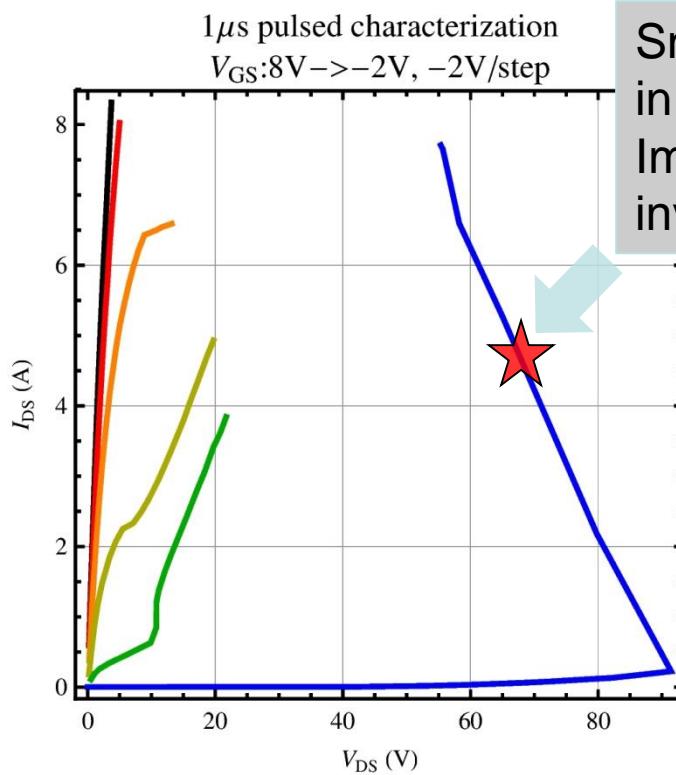
Both large-signal and small-signal RF characterization is carried out in order to evaluate device performance. RF stress are also carried out for reliability investigation



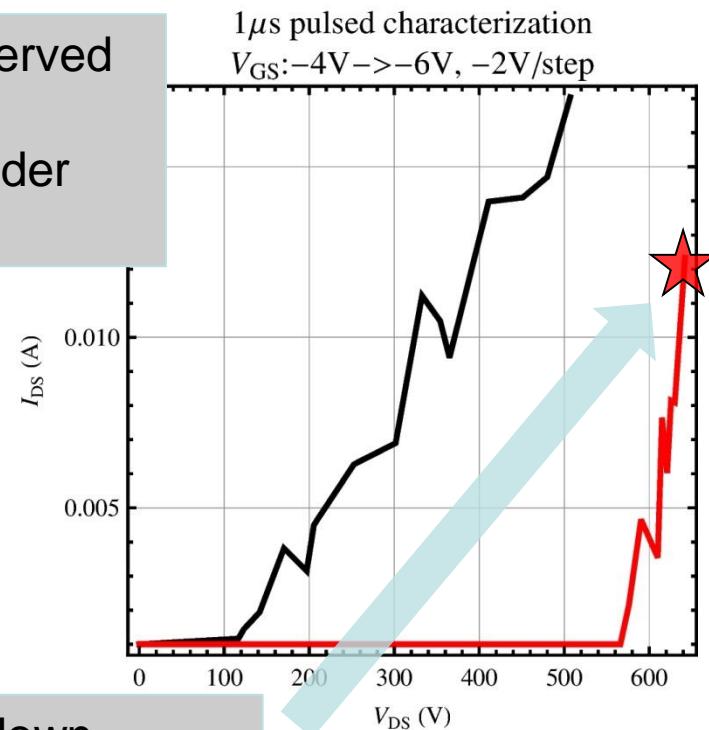


Breakdown Phenomena Investigation

Preliminary results on non-optimized large-periphery devices tested by applying short (1us) voltage pulses at the drain terminal.



Snap-back feature observed
in semi-off conditions
Impact Ionization?? Under
investigation...



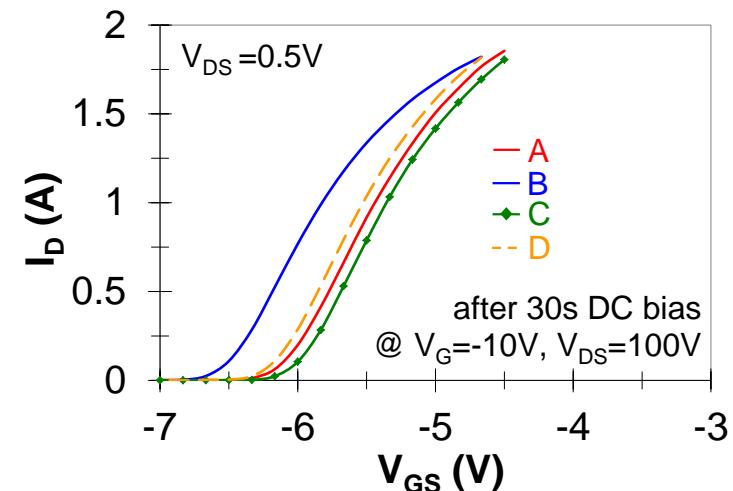
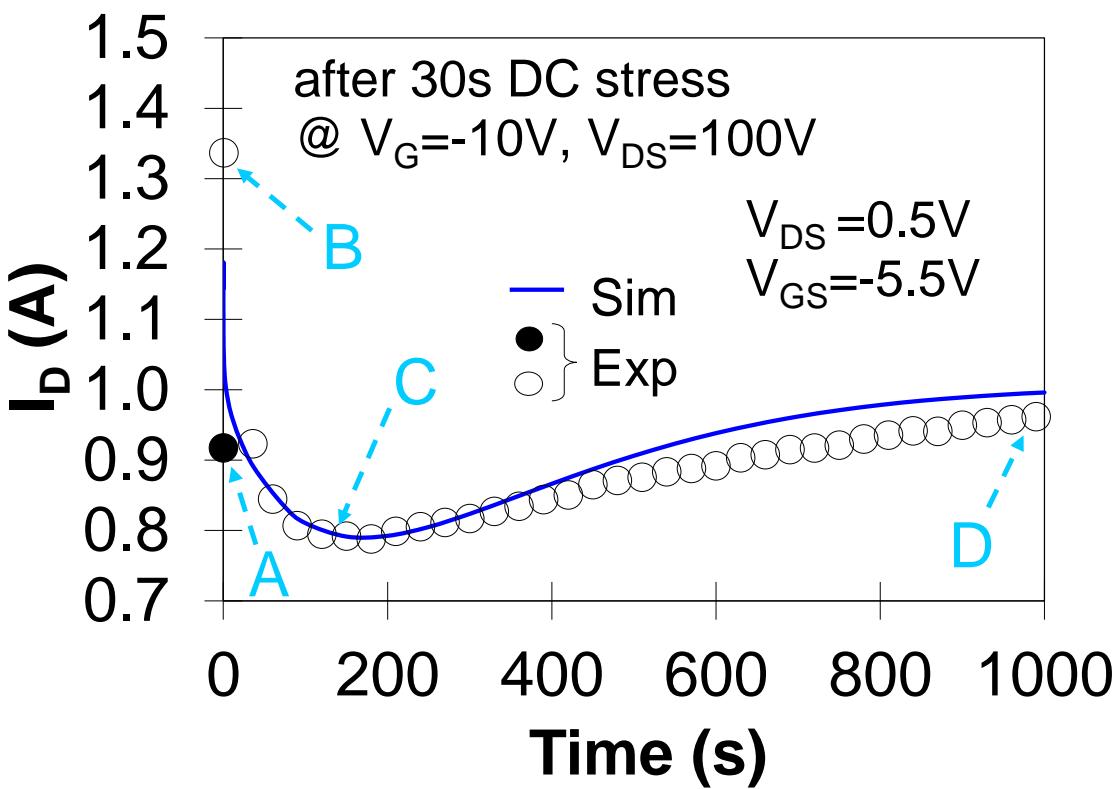
Destructive breakdown
occurring at 650V





A: pre-stress

B: neutral GaN:UID traps (no e^-) & neg. GaN:C traps (no h^+)



- B to C:** e^- capture into GaN:UID traps
- C:** neg. GaN:UID traps & neg. GaN:C traps
- C to D:** h^+ capture into GaN:C traps

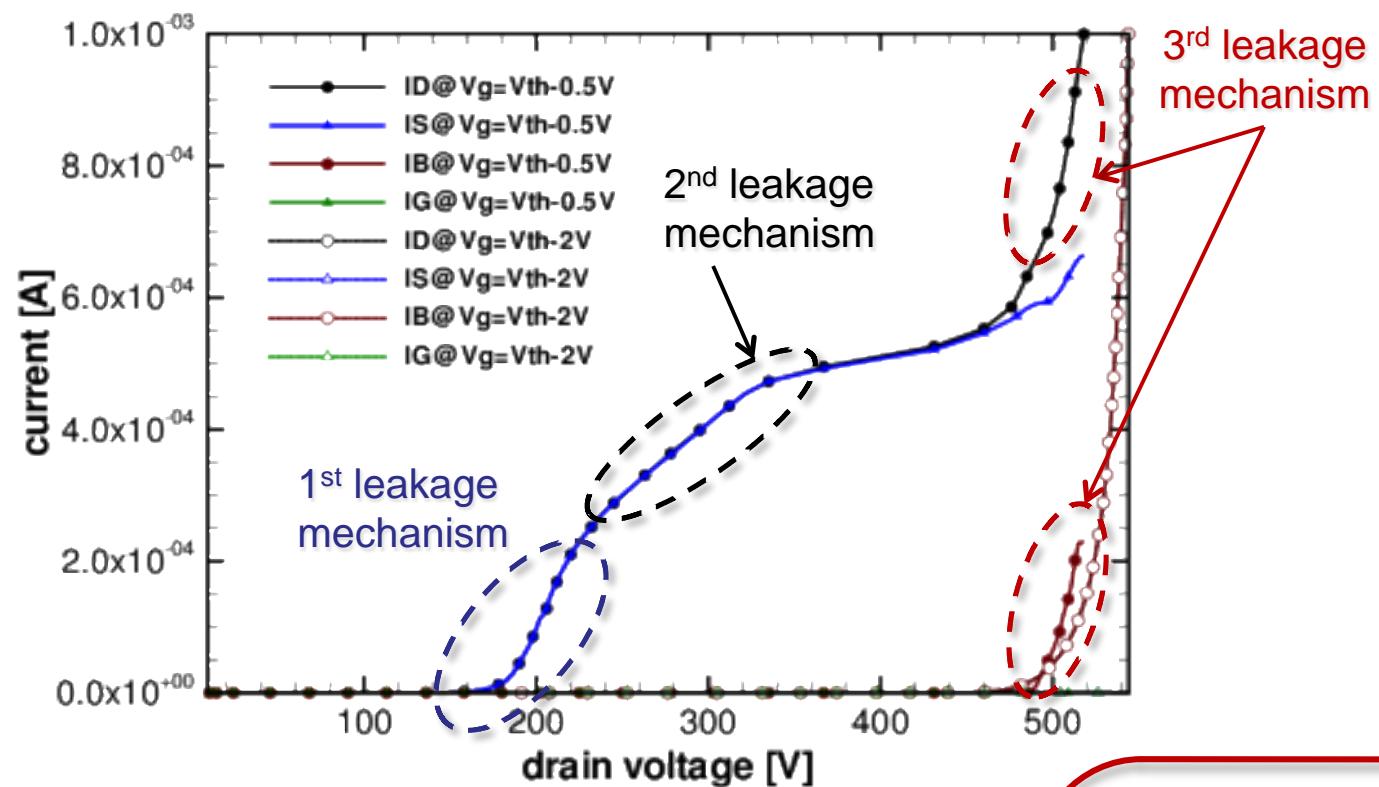




For $V_g = -6.5V$, at least three different breakdown/leakage mechanisms take place:

- 1) 1st BK: BTB, Impact Ionization, Poole-Frenkel related or something else?
- 2) 2nd BK: Back-barrier electron transfer
- 3) 3rd BK: BTB tunneling between drain & substrate

Whereas, for $V_g = -8V$ only the BTB phenomena between drain & substrate can be identified.

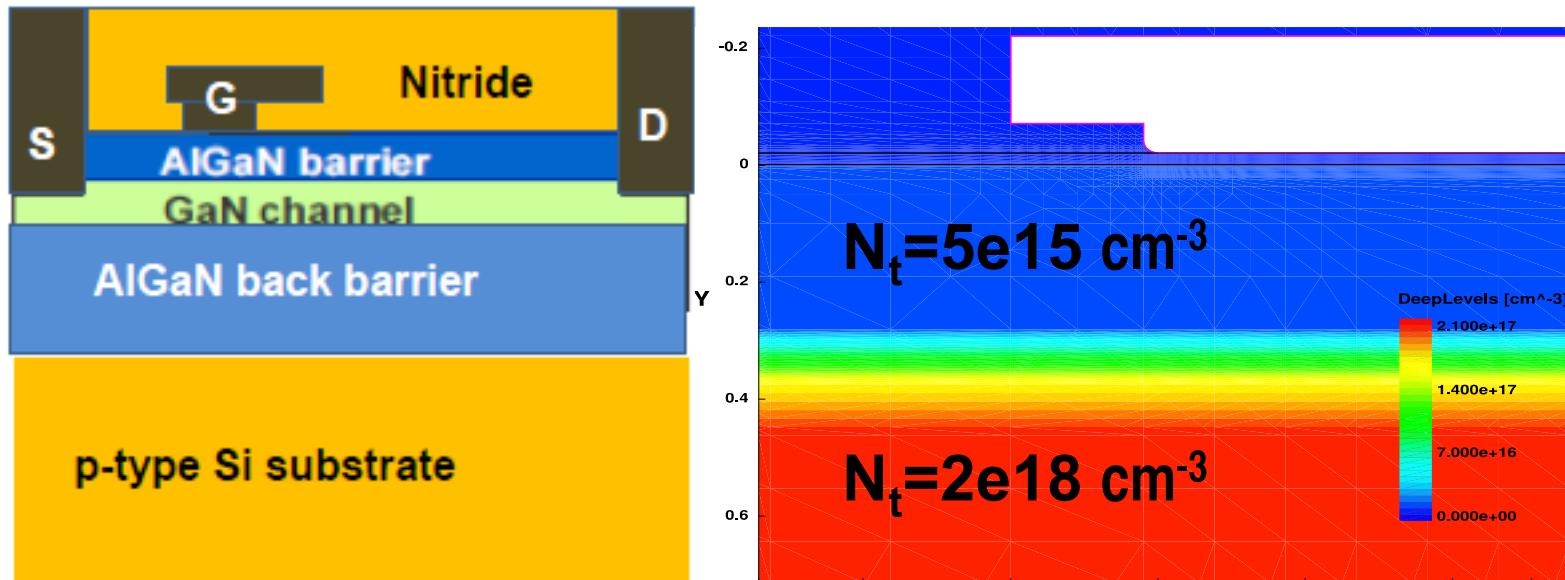


GaN-HEMTs - UniBO

Simulation of a GaN-on-Si power HEMT in off-state up to breakdown – Comparison against literature data

F. Monti, D. Cornigli, S. Reggiani, E. Gnani, A. Gnudi, G. Baccarani

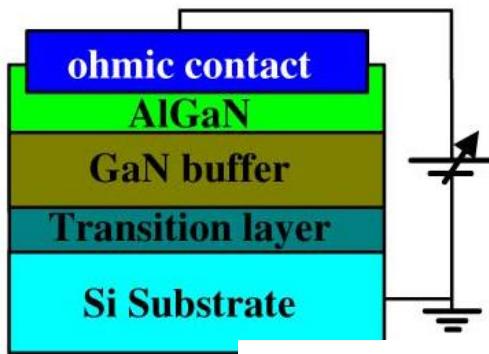
- Simulations with both electron and hole impact-ionization contributions
- Deep acceptor levels in the GaN buffer (0.4 eV above midgap) with a step-like distribution at 0.4um from the surface



GaN-HEMTs - UniBO

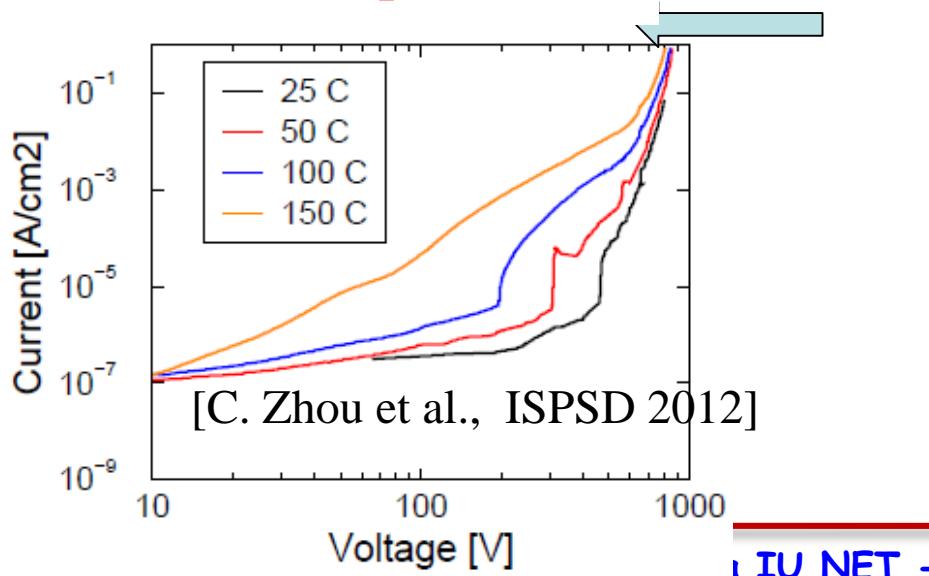
Simulation of vertical leakage/breakdown in GaN-on-Si buffers up to 150°C – Comparison against literature data

F. Monti, D. Cornigli, S. Reggiani, E. Gnani, A. Gnudi, G. Baccarani

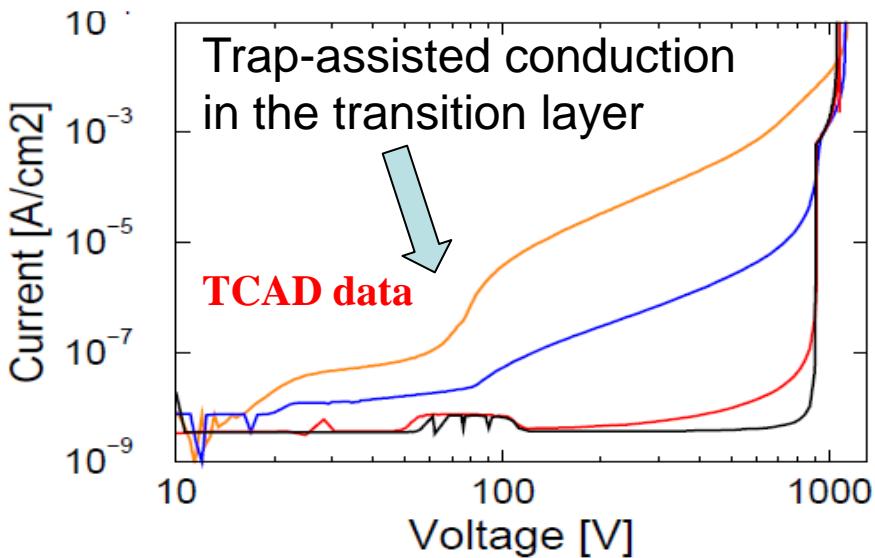
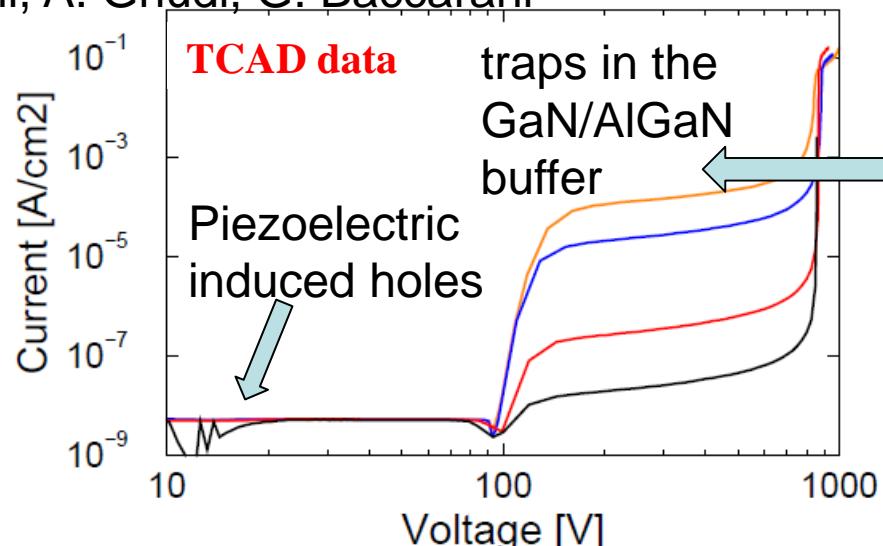


Vertical
buffer in
forward bias

Experiments



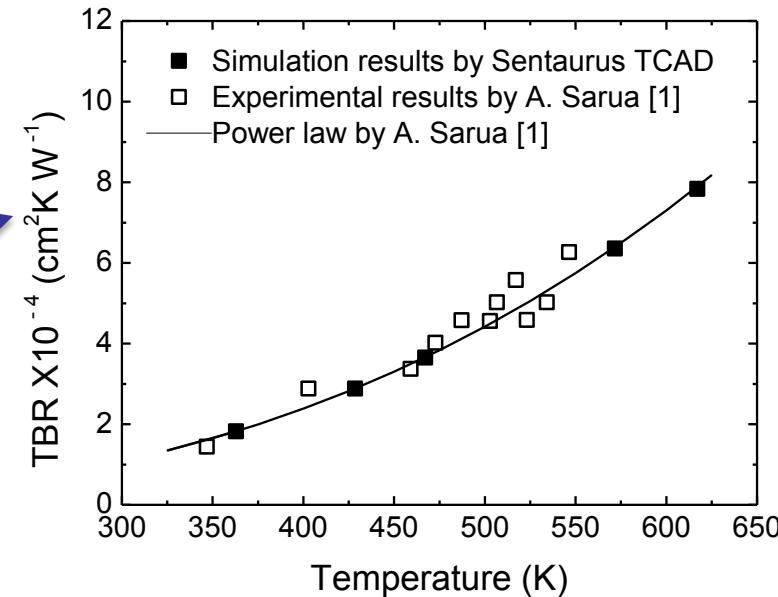
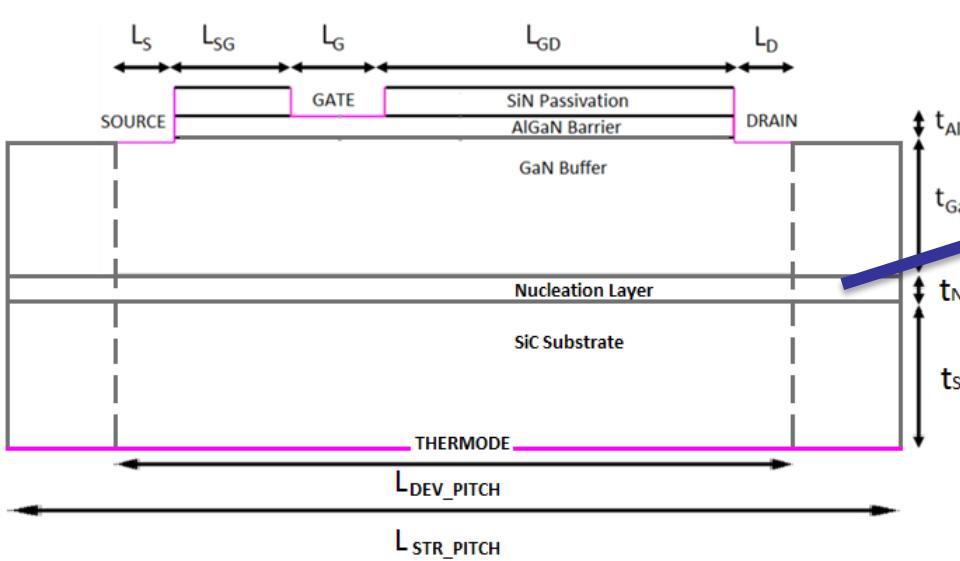
IU.NET



GaN-HEMTs - UniBO

Modeling Self-Heating Effects in AlGaN/GaN HEMT

A. N. Tallarico, P. Magnone, E. Sangiorgi, C. Fiega



- The TBR (thermal boundary resistance), between GaN layer and SiC substrate is modeled according to [1].
- PMI (physical model interface) implemented in Sentaurus TCAD [2]

[1] A. Sarua et al., *IEEE Trans. Electron Devices*, 2007

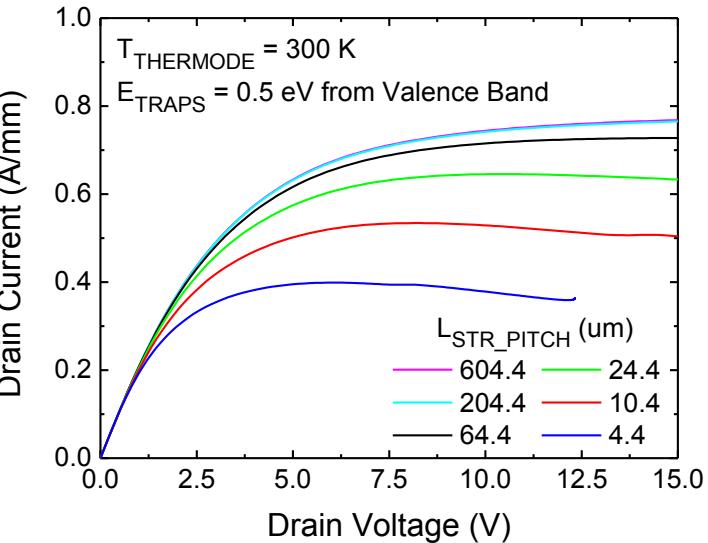
[2] A. N. Tallarico, SISPAD, 2014



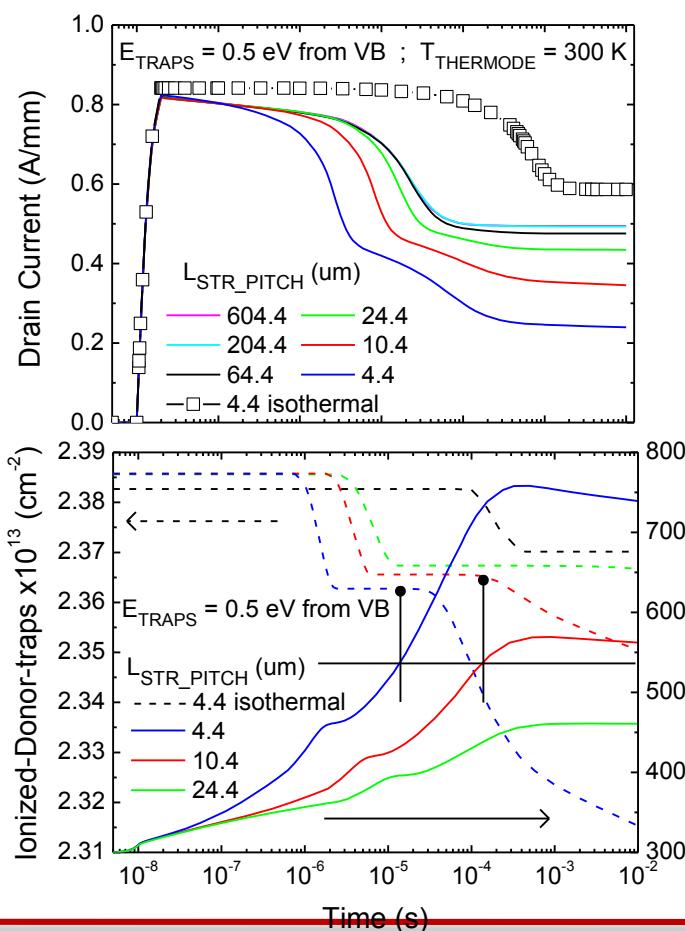
GaN-HEMTs - UniBO

Modeling Self-Heating Effects in AlGaN/GaN HEMT

Drain-lag simulations accounting for both self-heating and traps at AlGaN/Nitride interface



By reducing the pitch (distance between adjacent devices) because of the temperature increase a strong reduction of current is observed.

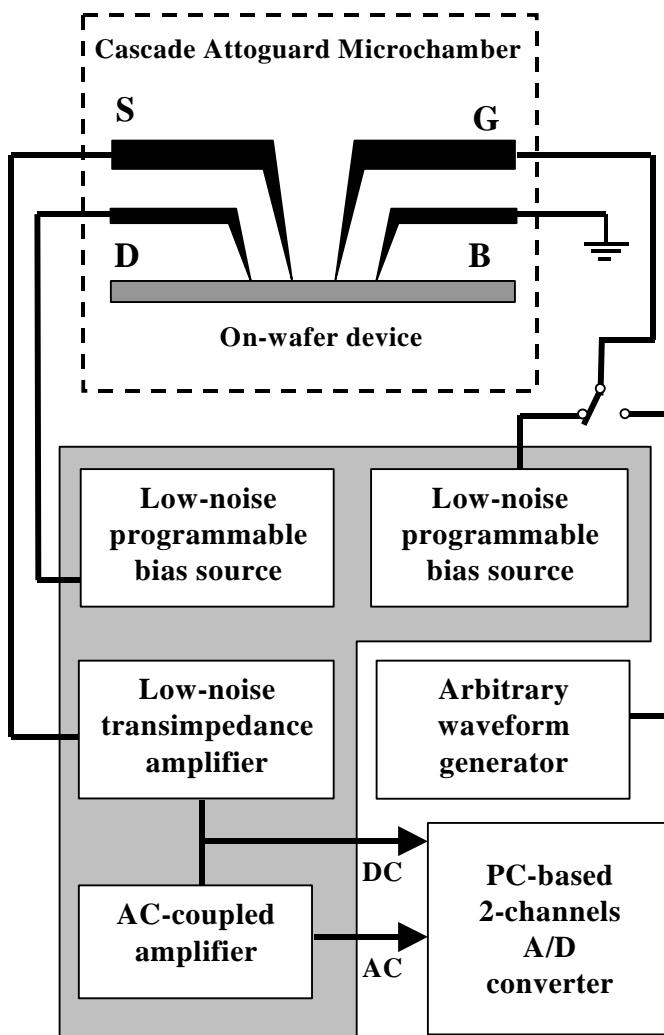


The current overshoot is linked to the transient of donor traps which is time-reduced and amplitude-increased for higher temperatures.

Two different transients:
- the first is intrinsic to the donor-traps,
- the second transient is a temperature-driven effect (activated at $T \approx 540 \text{ K}$).

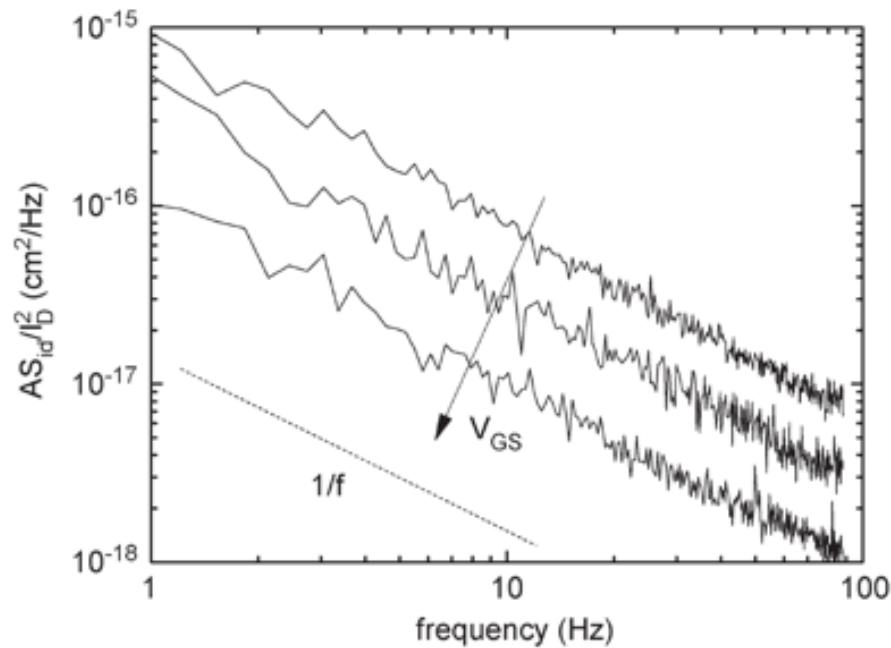


E2COGaN - Unical Contribution



1/f noise measurements on GaN devices

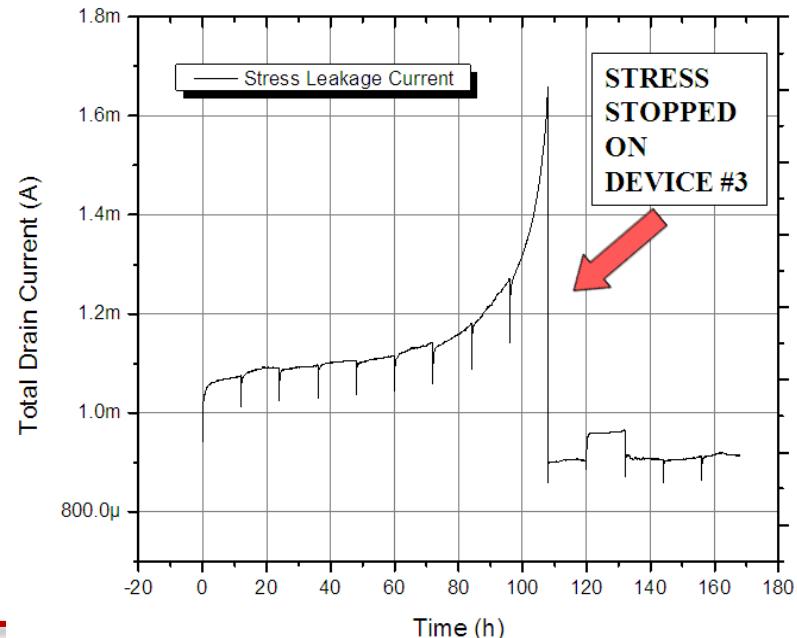
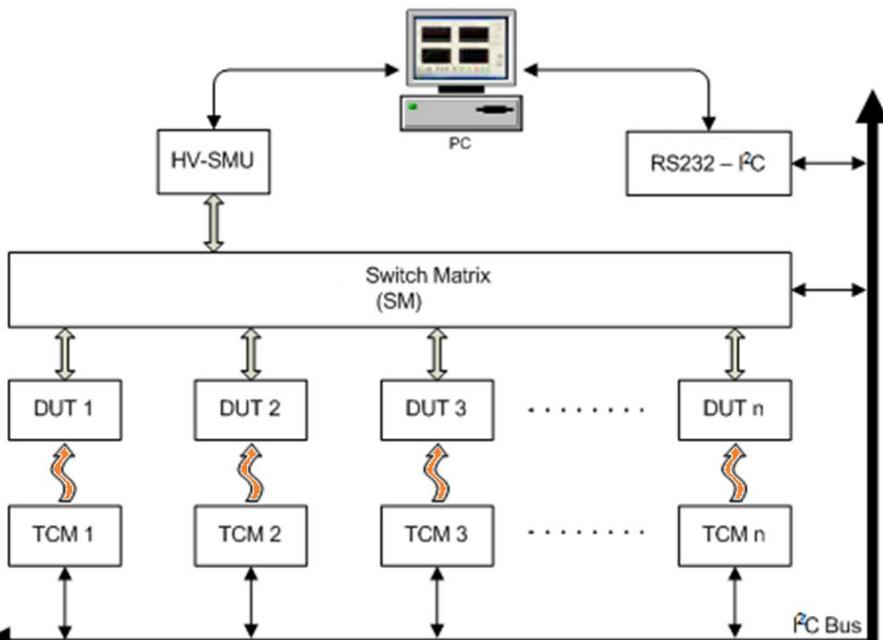
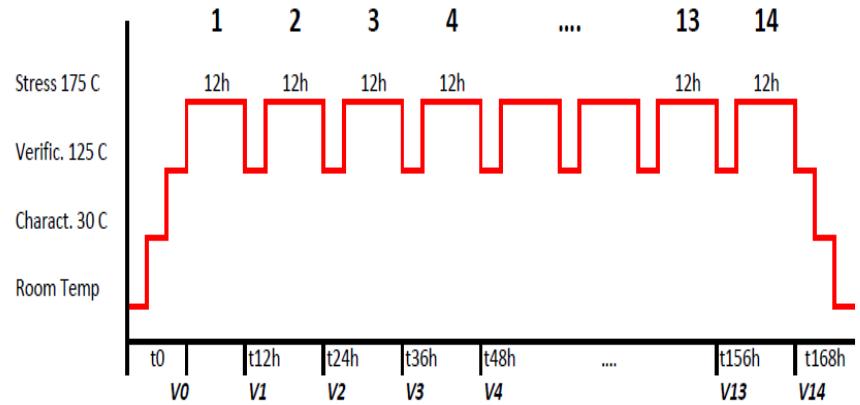
- Design and prototyping of instrumentation for low-frequency noise characterization
- Measurements of 1/f noise of gate and drain currents
- Evaluating trap density from 1/f noise in fresh and stressed devices



E2COGaN - Unical Contribution

Advanced HTRB characterization

- Individual device mini-heater for HTRB test with true constant T_C
- Individual stress-sense procedure up to a preset degradation threshold
- Large number of devices tested in parallel for statistical evaluation



Progetti Europei - Contratti - Collaborazioni



<http://www.alinwon-fp7.eu/fp7/>



<http://www.hiposwitch.eu/>



<http://www.e2cogan.eu/>



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